
EMX ®

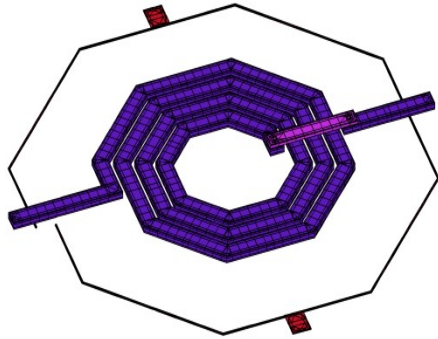
A Large-Scale Full-Wave Simulator for RF Designs

Integrand Software, Inc.
www.integrandsoftware.com

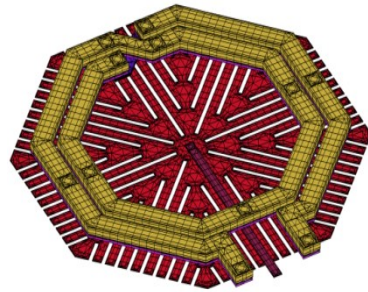
Integrand Software

- Integrand Software founded in 2003
- Founders from Bell Labs
- Formed company to target RF and RF IC design
- Focus on accuracy, speed and ease of use
- Successful company!
- Many of the world's major foundries and design houses now use the Integrand's products

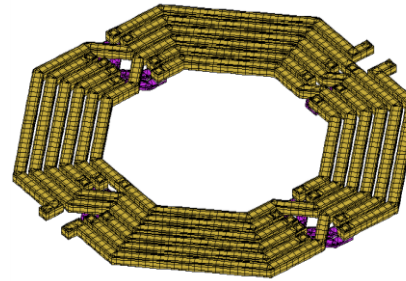
EMX modeling of passives



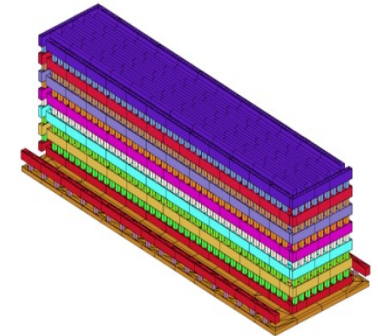
Inductor



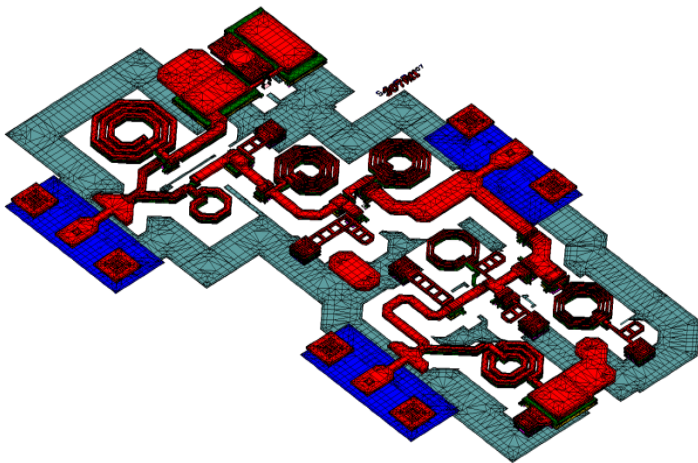
Shielding



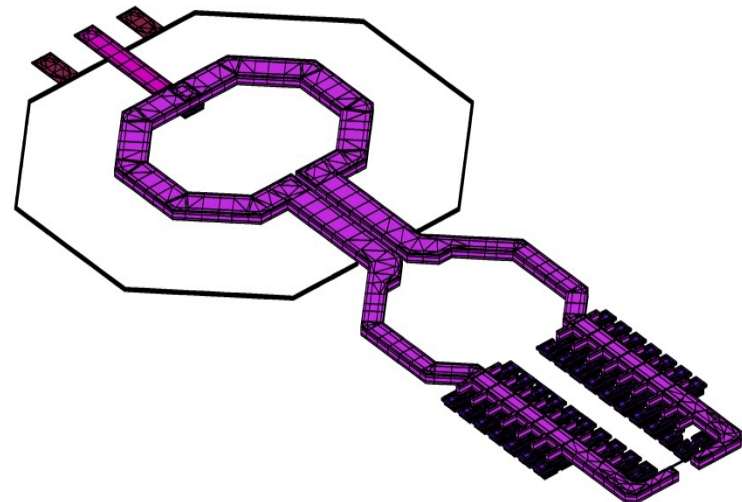
Transformer



MOM capacitor



Diplexer



VCO with capacitor bank

EMX (ElectroMagnetic EXtraction)

- Large scale full-wave, planar 3D electromagnetic simulator for verification and design of integrated circuits
- A powerful engine handles all electromagnetic effects in an unified manner
- Fast and very accurate
- Simulate full component ensembles with all couplings to avoid various sources of error
- Very easy to use
 - Mask Layout to S-parameters or spice models
 - Eliminates layers of intermediate steps and potential errors
 - Integrated into the Cadence Virtuoso® environment

EMX Customers



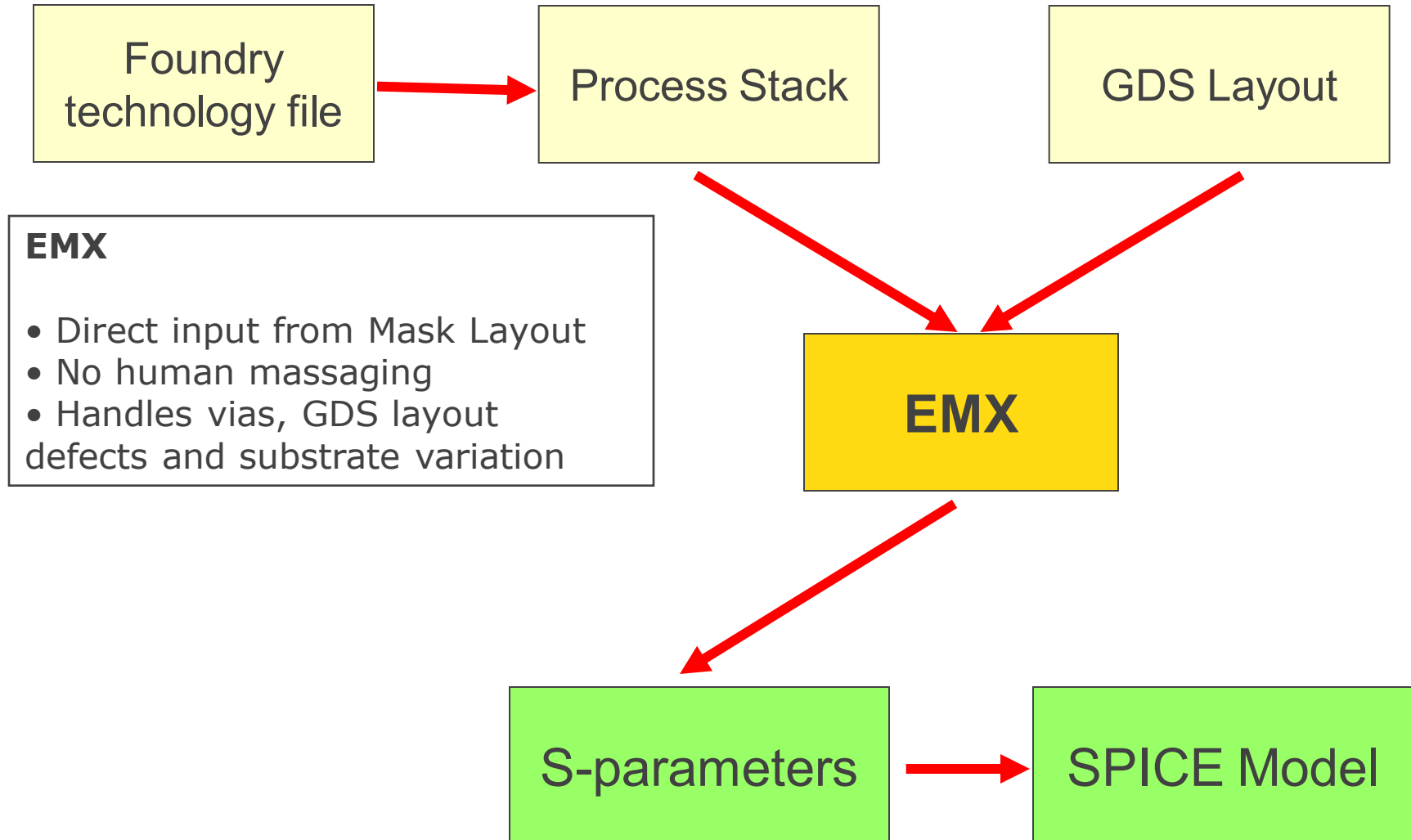
Foundry Relationships

- The world's major foundries have chosen EMX for characterization and models for passives.
- We have a very close relationship with the foundries
- Foundry qualifies technology files with measurements provides customers with technology files
- High accuracy can be guaranteed for the customers using the EMX design flow.
 - **TSMC** (180nm, 130nm, 90nm, 65/55nm, 45/40nm, 32/28nm CMOS, 20nm, 16nm, 10nm)
 - **UMC** (130nm, 90nm, 65nm, 45nm, 28nm CMOS)
 - **IBM** (180nm SiGe, 5PAE, 7WL, 9RF, 45nm CMOS)
 - **Global Foundries** (130nm to 14nm)
 - **TowerJazz** CA 18HR, SBC18HX, SBC18PTH
 - **ST** B9MW, H9SOIFEM, 14FDSOI, 28FDSOI

Difficulties with other EM tools

- Low Efficiency
 - Tradeoff between Accuracy and Computation Time/Expense. Traditional full-wave EM simulation is too long.
- Low Accuracy
 - Approximations are made to overcome inefficiency (2.5D methods), insufficient meshing or inaccurate matrix solution
 - Cannot handle true dielectric profiles with 10s of layers; often need to be approximated
- Not user-friendly
 - Cannot handle true mask GDSII layout with vias, slotting rules, dummy fill, etc.
 - Demand lots of human effort to “massage” layout, such as , merging vias, removing fill, simplifying the geometry so that the simulator can accept the input.
 - Simple user interface to Cadence Virtuoso®

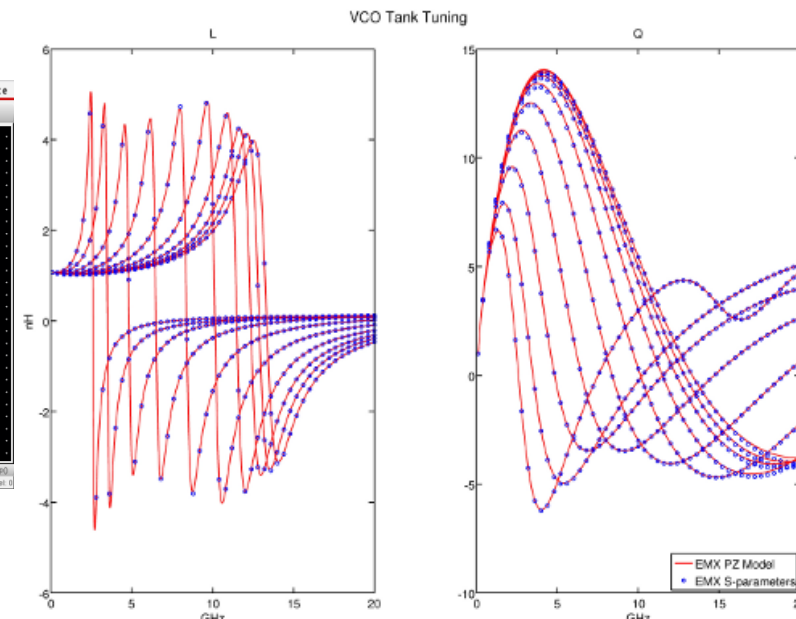
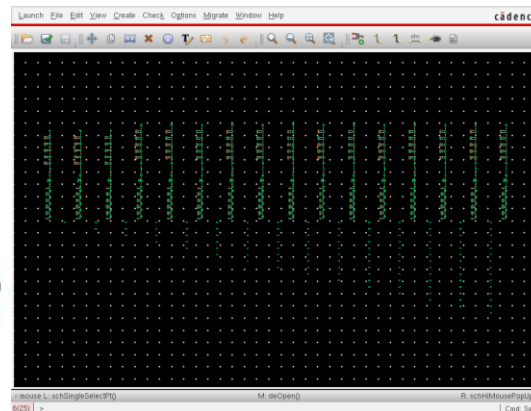
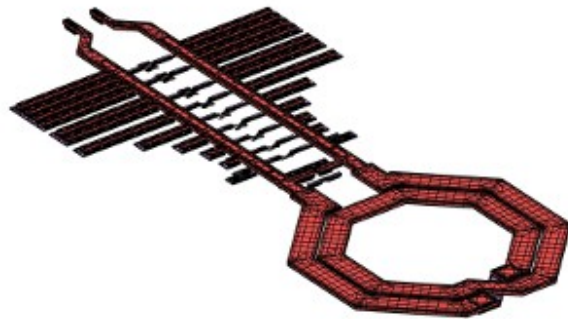
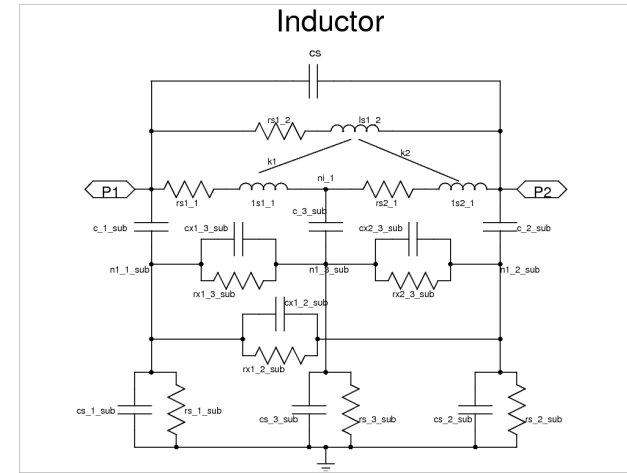
EMX Design Flow



Models

- The results of EMX can be used in higher level Spice simulators like Spectre
- EMX can generate three kinds of models
 1. S-parameters
 2. RLCK models for basic passive s (inductors, baluns, caps)
 - Used by major foundry PDKS (TSMC, GF, UMC, IBM).
 - Physical topology
 3. RCLK + Control sources (pole zero models): VCOs, LNAs
 - Non-physical topology
- S-parameters are the most accurate result
- RLCK template models are used for transient analysis when S-parameters result in non-convergence in the time domain
- PZ models are used when the lumped models don't suffice (multiport circuits, e.g., 20 ports)

- Pole Zero models



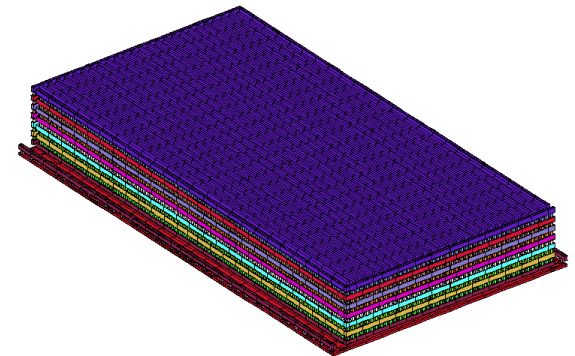
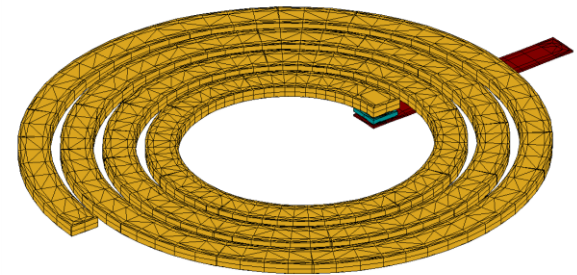
Distinguishing features of EMX

1. Accuracy
 - Uncompromised accuracy in solving Maxwell's equations
2. Speed
 - The fastest EM simulator, based on the Fast Multipole Method
3. Easy to use
 - Easy to use from within Cadence or from command line scripting

Accuracy (Electromagnetics)

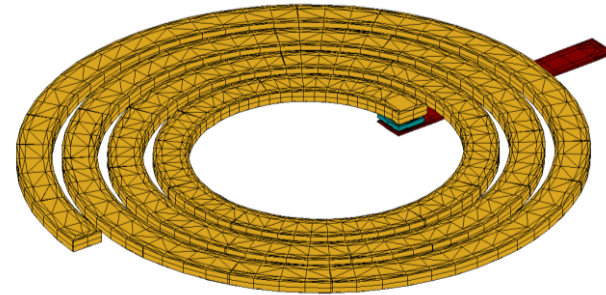
- All physical effects included
 - R, L, C, substrate in a fully coupled manner
- Inductance
 - Distributed 3D volume currents
- Resistance
 - Skin effect and volume loss
- Capacitance
 - Accurate side-wall capacitance
 - MIM and thin-film capacitors
- Substrate
 - Multi layered lossy substrates
 - Substrate doping and bias
- Vias
 - Via inductance and capacitance

$$E_s(r) = \frac{1}{\sigma} J(r) + j\omega A(r) + \nabla\phi(r)$$



Speed (Numerics)

- Integral Equation-based
- 3D EM Field Solver
 - Preconditioned iterative methods
 - New “Full-Wave” FMM
 - Layout-regularity exploited
 - Adaptive Fast Frequency Sweep using Krylov subspace techniques
- Speed
 - 2 orders of magnitude faster than finite-element tools
 - 1 order faster than BEM
 - Even faster with multi-threading



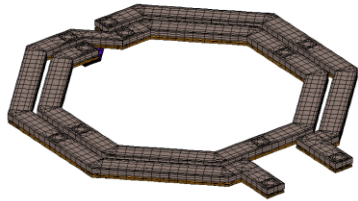
9244 basis functions
13692 vector potential elements
4877 scalar potential elements

| Freq. Range | Simulation | Time | Memory |
|---------------|-------------|--------|--------|
| 5 GHz | 1 | 40 sec | 7 MB |
| 0.1 to 20 GHz | Sweep (201) | 90 sec | 22 MB |

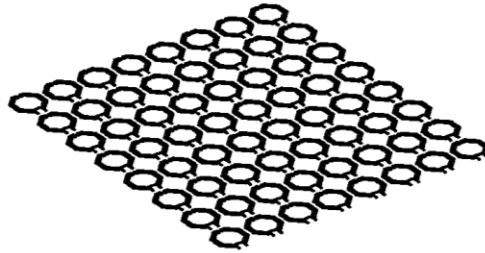
AMD Athlon XP 3200
2.2 GHz, 1GB RAM

-

Time and Memory scaling

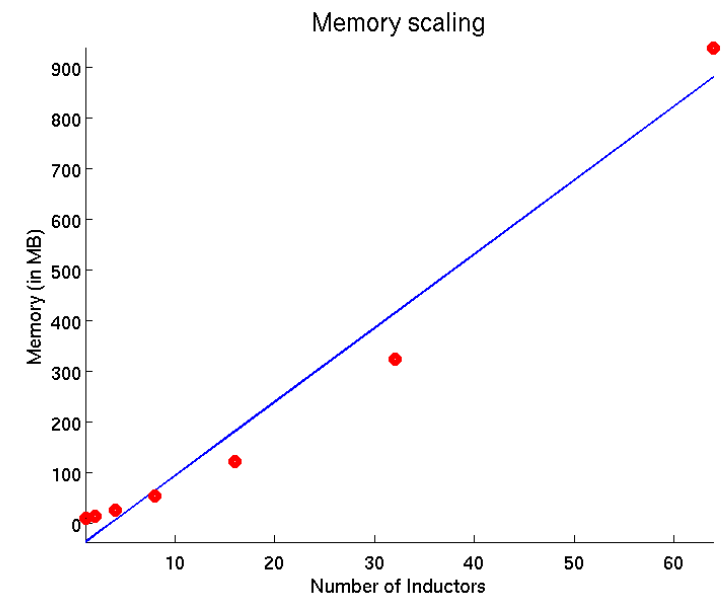
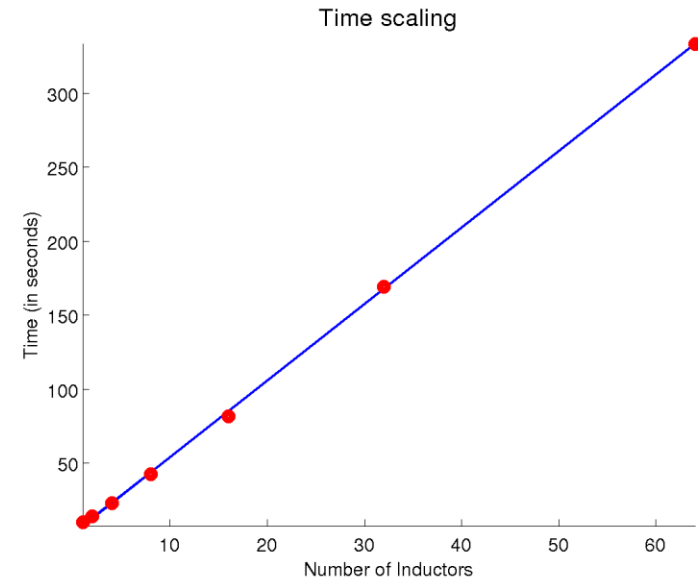


1 inductor



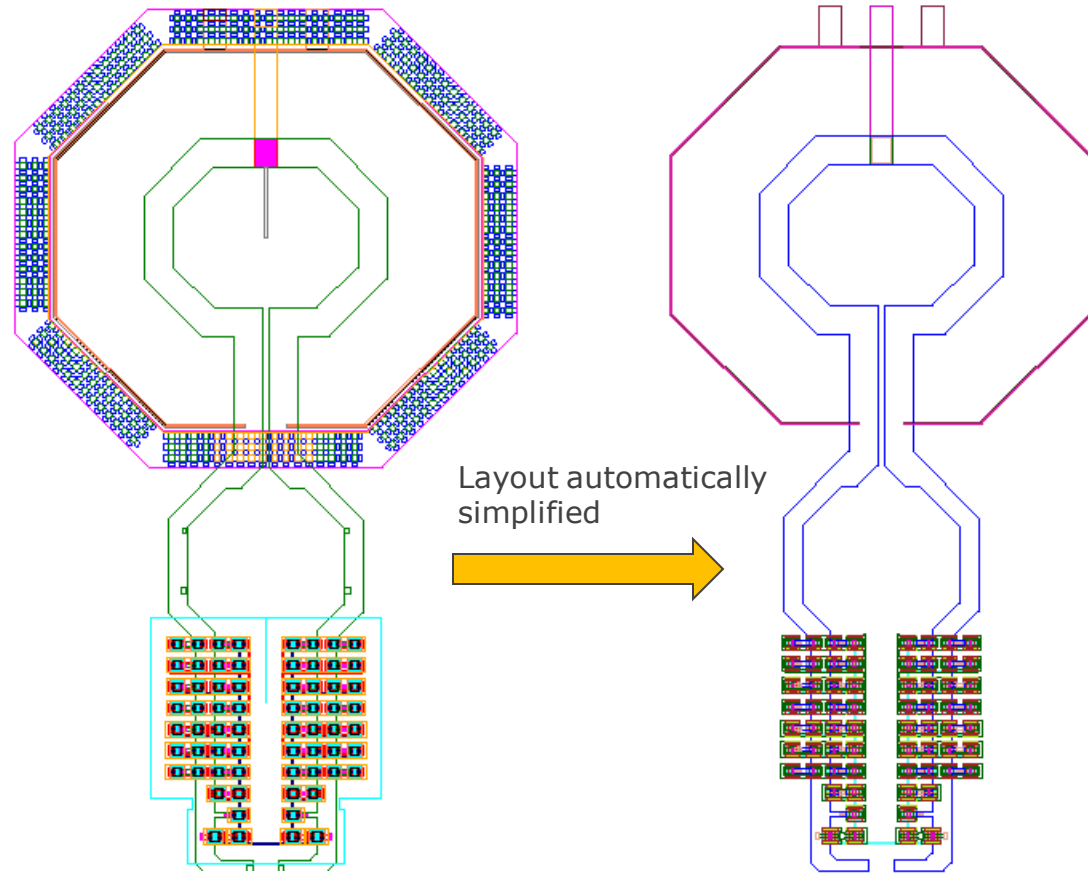
64 inductors

- Single frequency simulation (including iterative solve)
- Compare speed and memory for 1, 2, 4, 8, ..., 64 inductors



Easy to Use

- EMX accepts true mask layout and will automatically simplify the layout for meshing and EM simulation
 - Via arrays, slotting rules, metal fill simplified
 - Boolean masking operations can be performed
 - Can apply grows and shrinks to the geometry including half-node scaling and metal bias
- **What goes to mask goes to simulator!**



Vias merged
Fill removed
Metal bias applied
MiM cap bank
handled

- h=∞, ε=1
h=0.25 μm, ε=4.2
h=0.075 μm, ε=7.8

259.080
258.755

metal9

h=3 μm, ε=4

255.645

via8

h=0.11 μm, ε=7.8
h=0.725 μm, ε=4

254.845

metal8

h=0.075 μm, ε=7.8

254.020

metal8

h=0.775 μm, ε=4

via7ctm
ctm
cbm

via7

via7cbm
cbm

h=0.05 μm, ε=7.8
h=0.62 μm, ε=4

253.350

metal7

h=0.05 μm, ε=5
h=0.25 μm, ε=3

253.000

via6

h=0.1 μm, ε=3
h=0.03 μm, ε=4

252.920

metal6

h=0.05 μm, ε=5
h=0.25 μm, ε=3

252.570

via5

h=0.1 μm, ε=3
h=0.03 μm, ε=4

252.490

metal5

h=0.05 μm, ε=5
h=0.25 μm, ε=3

252.140

via4

h=0.1 μm, ε=3
h=0.03 μm, ε=4

252.060

metal4

h=0.05 μm, ε=5
h=0.25 μm, ε=3

251.710

via3

h=0.1 μm, ε=3
h=0.03 μm, ε=4

251.630

metal3

h=0.05 μm, ε=5
h=0.25 μm, ε=3

251.280

via2

h=0.1 μm, ε=3
h=0.03 μm, ε=4

251.200

metal2

h=0.05 μm, ε=5
h=0.25 μm, ε=3

250.850

via1

h=0.1 μm, ε=3
h=0.03 μm, ε=4

250.770

metal1

h=0.05 μm, ε=5
h=0.13 μm, ε=3

250.610

polycont
poly

diffcont

h=0.03 μm, ε=4.5
h=0.31 μm, ε=4

250.300

diff

h=0.3 μm, ε=3.9

250.000

h=250 μm, ε=11.9, 12.5 Ω-cm, 8 S/m

0.000

via7ctm: h=0.0273 μm, 0.5 Ω/via
via7cbm: h=0.145 μm, 0.5 Ω/via
via8: h=0.91 μm, 0.4 Ω/via
via7: h=0.495 μm, 0.2 Ω/via
via6: h=0.18 μm, 2 Ω/via
via5: h=0.18 μm, 2 Ω/via
via4: h=0.18 μm, 2 Ω/via
via3: h=0.18 μm, 2 Ω/via
via2: h=0.18 μm, 2 Ω/via
via1: h=0.18 μm, 2 Ω/via
polycont: h=0.17 μm, 20 Ω/via
diffcont: h=0.504 μm, 26 Ω/via

metal9: h=3 μm, 6 mΩ/sq
metal8: h=1 μm, 20 mΩ/sq
ctm: h=0.1 μm, 20 Ω/sq
cbm: h=0.2 μm, 0.5 Ω/sq
metal7: h=0.25 μm, 0.18 Ω/sq, bias 10 nm
metal6: h=0.25 μm, 0.18 Ω/sq, bias 10 nm
metal5: h=0.25 μm, 0.18 Ω/sq, bias 10 nm
metal4: h=0.25 μm, 0.18 Ω/sq, bias 10 nm
metal3: h=0.25 μm, 0.18 Ω/sq, bias 10 nm
metal2: h=0.25 μm, 0.18 Ω/sq, bias 10 nm
metal1: h=0.18 μm, 0.2 Ω/sq, bias 5 nm
poly: h=0.1 μm, 14.9 Ω/sq, bias -0.5 nm
diff: h=0.086 μm, 16.9 Ω/sq

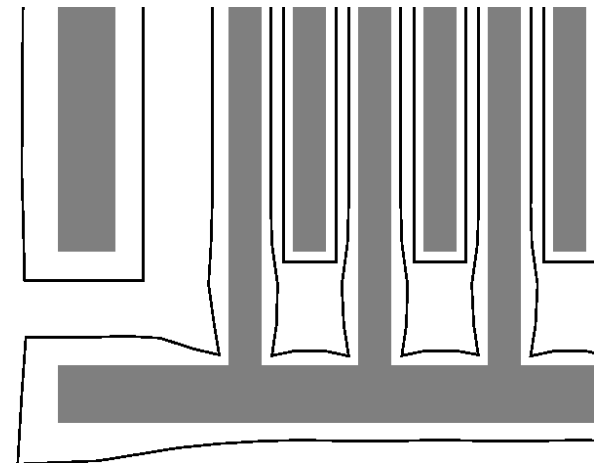
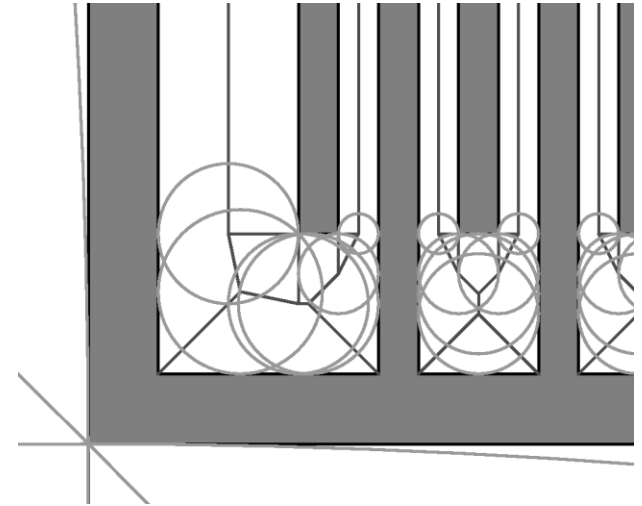
$h=250\text{ }\mu\text{m}$, $\epsilon=11.9$, $12.5\text{ }\Omega\text{-cm}$, 8 S/m

TSMC iRCX technology files

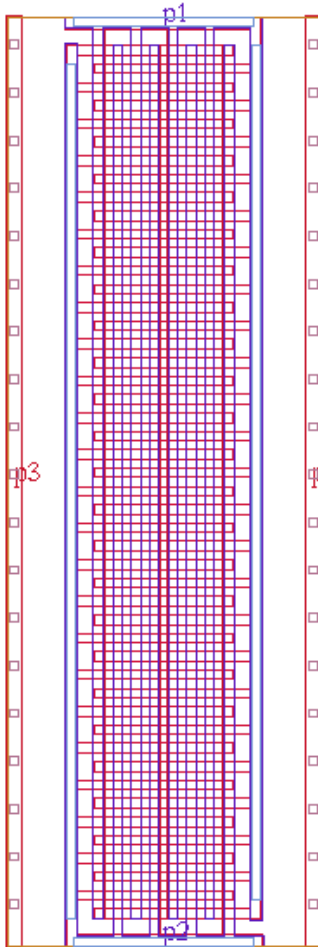
- Accurate process parameters are critical for EM simulation
- TSMC iRCX file provides a detailed process information
 - Metal, dielectric properties
 - Temperature dependence
 - Statistics and corner cases
 - Width-spacing dependent properties
 - Designer does not have to enter information from design manual
 - Removes sources of error
- Width and spacing properties (paper at RFIC 09 with TSMC)
 - Mimics fabrication process
 - shows that this significantly improves simulation accuracy for passive components like inductors and MOM capacitors.

Mimicking the TSMC fabrication in EMX

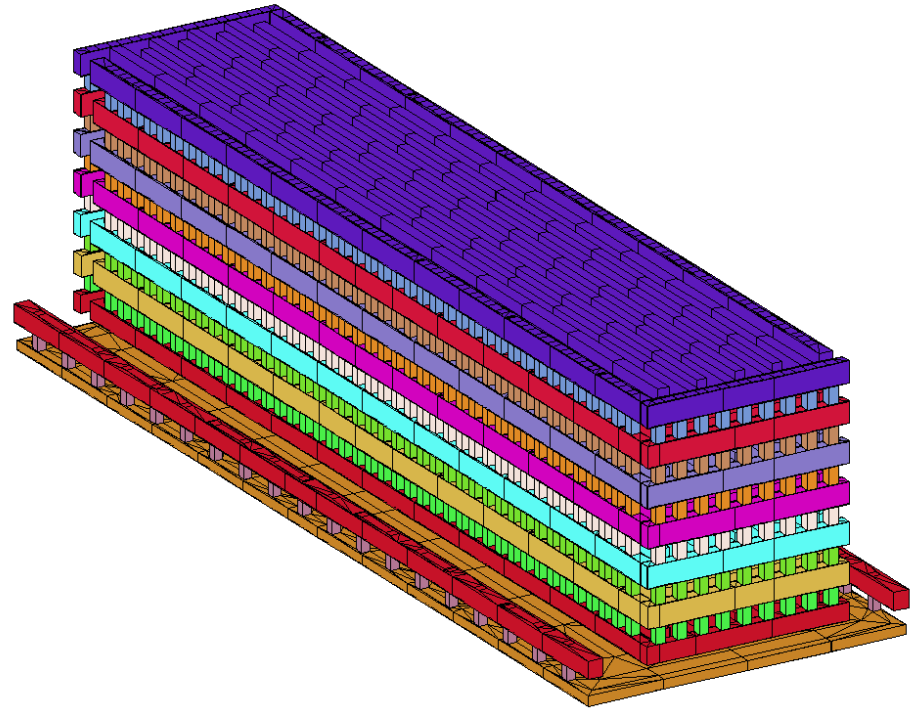
- EMX uses Voronoi diagrams to capture the width-and-spacing dependent parameters in the iRCX files
- These Voronoi diagrams are used to alter the drawn layout to mimic the fabrication process
- The shaded region shows the “drawn” layout and the “line” shows the modified layout according to the iRCX rules



Typical TSMC MOM capacitor and EMX mesh



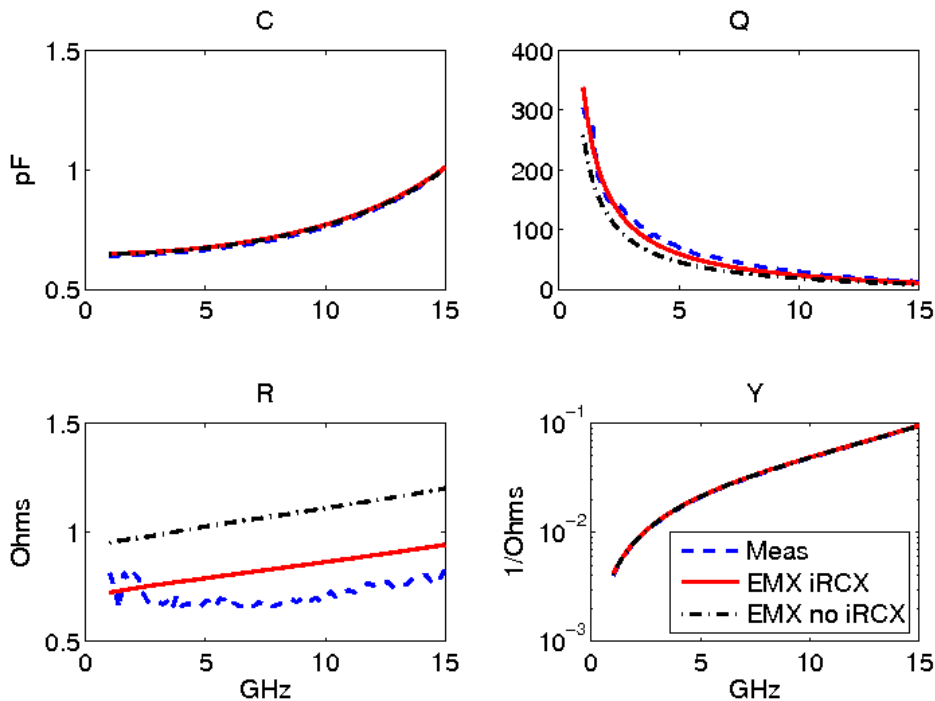
gdsview



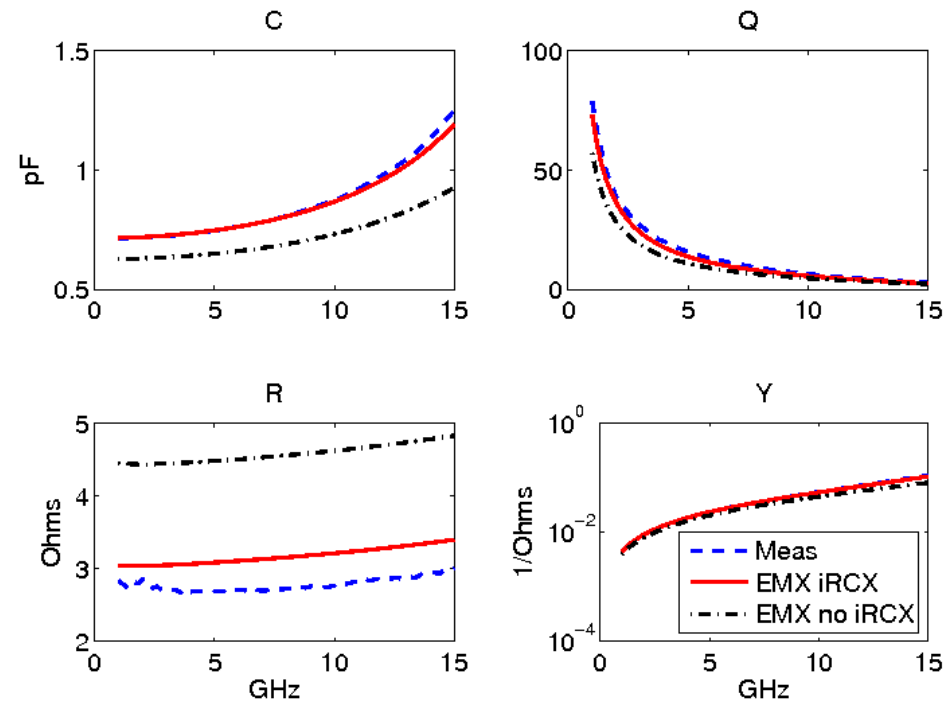
EMX 3D Mesh

EMX simulation of MOM capacitors

Capacitor MOM06: $w=0.1$, $s=0.1$



Capacitor MOM36: $w=0.1$, $s=0.16$



The iRCX width-and-spacing dependence is more critical for structures that are not at minimum dimensions. The accuracy of EMX using iRCX is increased since the fabrication process is mimicked more closely.

Easy to use: Virtuoso interface

The image displays the Integrand Virtuoso interface, which is used for circuit design and simulation. The interface is divided into several sections:

- Left Panel (Configuration):** Contains various settings for the simulation and design.
 - Process:** Set to `c:\interface\processes\generic65.prod`.
 - X-section:** ☒ Scaled, ☐ Unscaled.
 - GDS view:** ☒ EMX, ☐ Raw.
 - Accuracy options (all lengths in microns):**
 - Edge mesh: 1
 - Thickness: 1
 - Via merge: 0.5
 - 3D metals: 4
 - Ports:** Signals: P1, P2; Grounds: .
 - Frequency range (all frequencies in Hertz):**
 - Start: 1e+00
 - Stop: 2e+10
 - Step: 1e+00
 - Output:**
 - Types: ☒ S-parameters, ☐ Y-parameters
 - Formats: ☒ Touchstone, ☐ Spectre, ☐ Matlab
 - Advanced options:** Simulation: Start, Status, Stop.
 - Data import:** Data file: ; Browse...
 - Import for:** fitting, comparison.
 - Plotting and model creation:** Type: Single-ended inductor.
 - Plot:** Waveform viewer.
 - Create model:** Start, Status, Stop.
 - Create symbol and schematic:** Form state: Save, Load.
- Top Panel (Design View):** Displays the circuit design on a grid. The design is a complex, symmetrical structure, likely a filter or a matching network, rendered in green. The top status bar shows coordinates (X: -136.4, Y: -22.0), (F) Select: 0, DRD: OFF, dX: , dY: , Dist: , and Cm.
- Bottom Panel (Command Line):** Shows the command line interface with the following commands:


```
mouse L: mouseSingleSelectPt
M: leHiMousePopUp()
R: deOpen()
```

A red arrow points from the "Edge mesh" field in the left panel to the design view, indicating the relationship between the mesh size and the design resolution.

Seamless interface to Virtuoso

Easy to use: Running EMX using a script

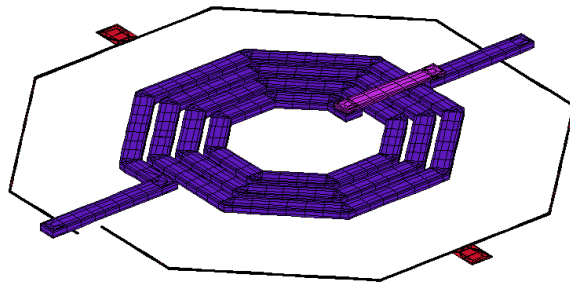
- Some customers use EMX using simple shell scripts or the command line

```
gdsfile=testind.gds
process=RC_IRCX_CRN65LP_1P8M+ALRDL_6X1U_typ.proc
freqs="--sweep 2e8 20e9 --sweep-stepsizes 2e8"
opts="--verbose=3 -e 1 -t 1 --3d=* -v 0"
emx $gdsfile.gds testind $process.proc --touchstone -s $gdsfile.s2p $opts
```

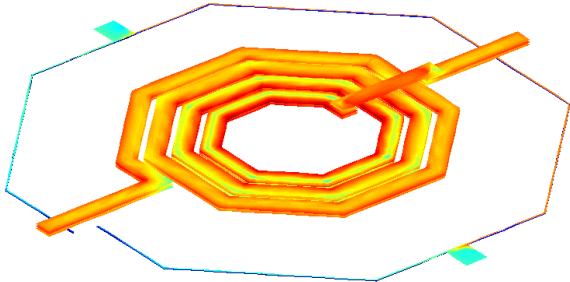
- Jobs can be submitted in queues to do extensive analysis
- Fast and easy to use

Benchmarks: Spiral Inductor

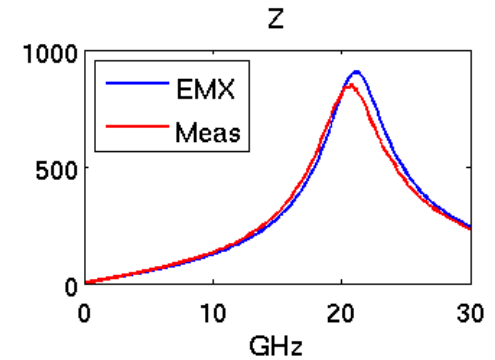
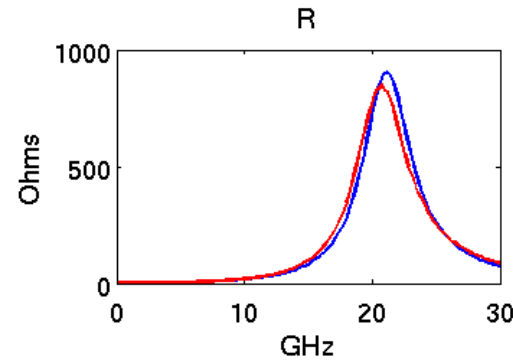
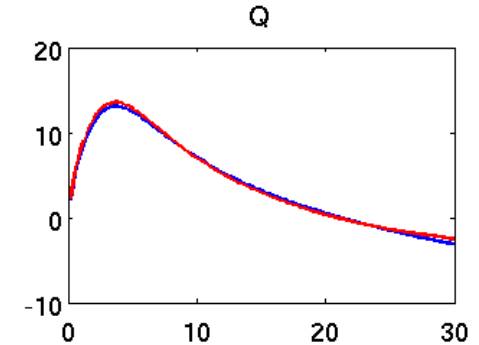
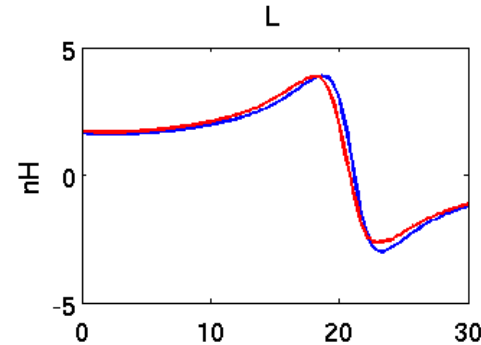
Spiral Inductor



3D mesh



Current

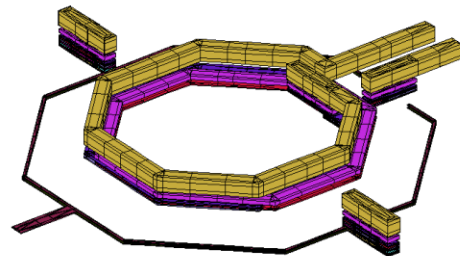


| Example | Ports | Freq Range | Size | 1 CPU | | 8 CPUs | |
|-----------------|-------|--------------|--------|-------|-------|--------------|--------------|
| | | | | Mem. | Time | Mem. | Time |
| Planar Inductor | 2 | 0.2GHz-30GHz | 13,181 | 193MB | 3m29s | 790MB | 1m48s |

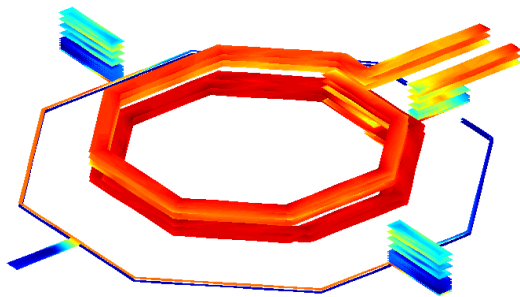
Courtesy: TSMC. 65nm RFCMOS, 9LM thick metal technology. Published at RFIC 2009

"Including Pattern-Dependent Effects in Electromagnetic Simulations of On-Chip Passive Components", Integrand and TSMC

Stacked Inductor

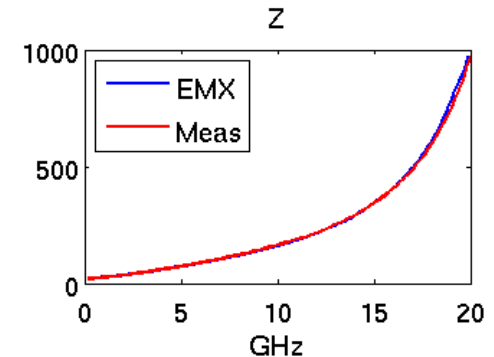
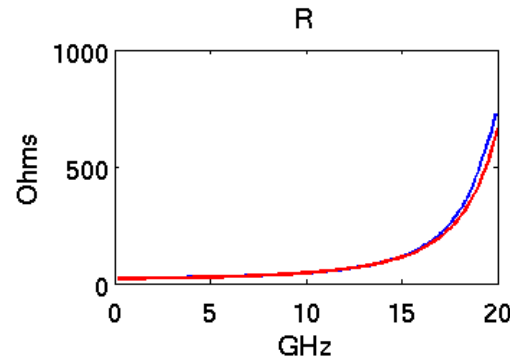
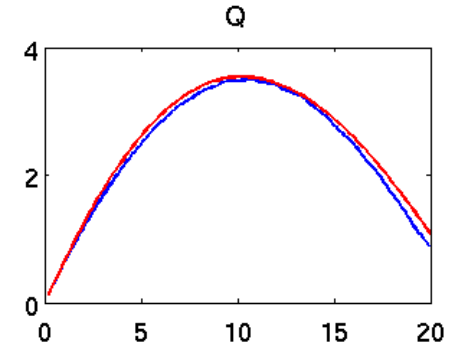
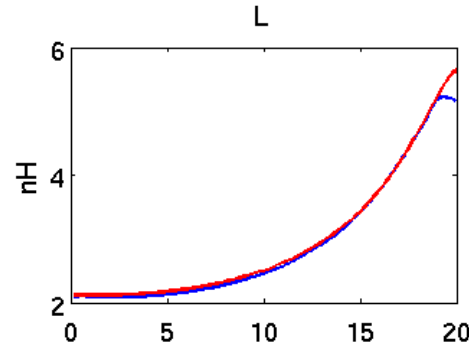


3D mesh



Current

Stacked inductor

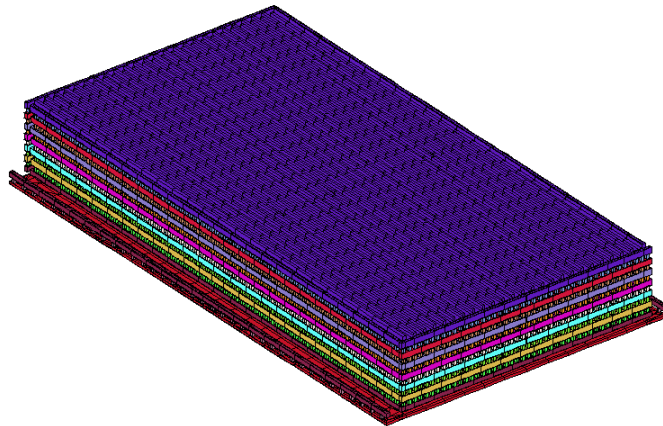


| Example | Ports | Freq Range | Size | 1 CPU | | 8 CPUs | |
|------------------|-------|--------------|--------|-------|-------|--------------|--------------|
| | | | | Mem. | Time | Mem. | Time |
| Stacked Inductor | 2 | 0.2GHz-20GHz | 10,407 | 453MB | 6m58s | 688MB | 4m42s |

Courtesy: TSMC. 65nm RFCMOS, 9LM thick metal technology. Published at RFIC 2009

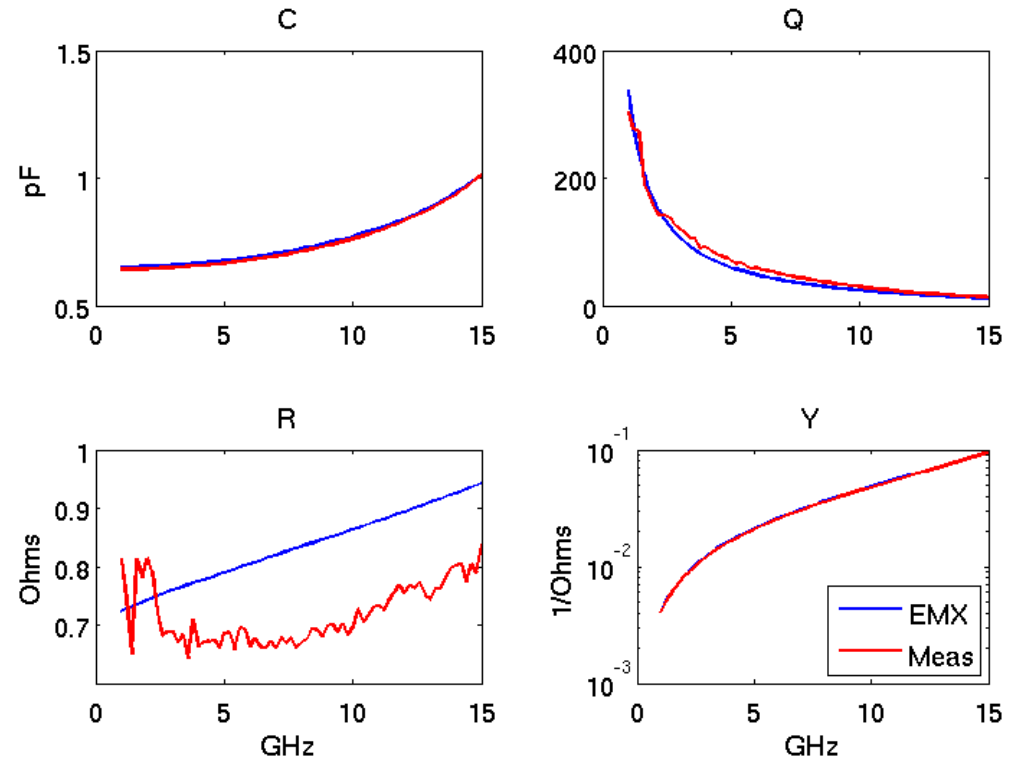
"Including Pattern-Dependent Effects in Electromagnetic Simulations of On-Chip Passive Components", Integrand and TSMC

MOM (finger)Capacitor



3D mesh of 0.6pF Cap

Capacitor MOM06: w=0.1, s=0.1

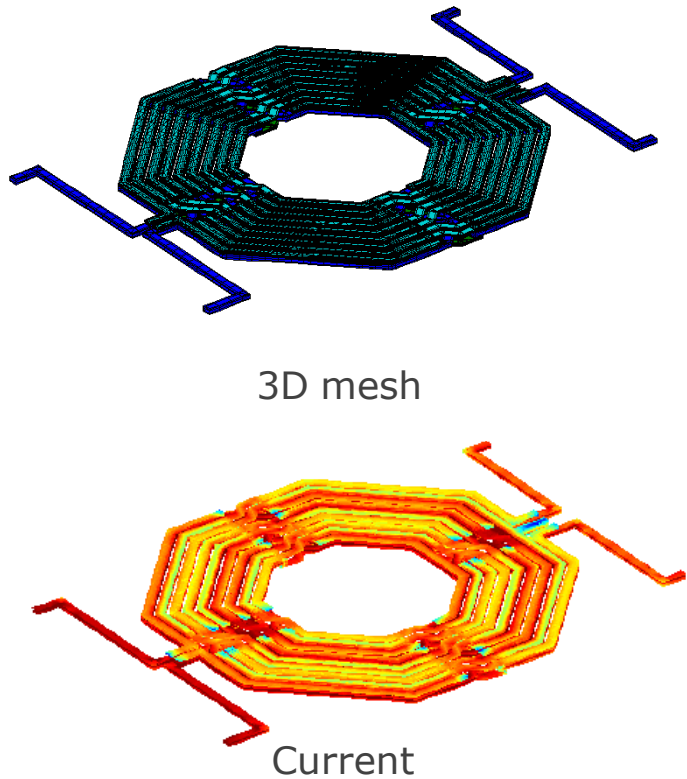


| Example | Ports | Freq Range | Size | 1 CPU | | 8 CPUs | |
|---------------|-------|--------------|--------|--------|--------|---------------|--------------|
| | | | | Mem. | Time | Mem. | Time |
| MoM capacitor | 2 | 0.2GHz-20GHz | 48,997 | 1140MB | 19m12s | 2591MB | 5m59s |

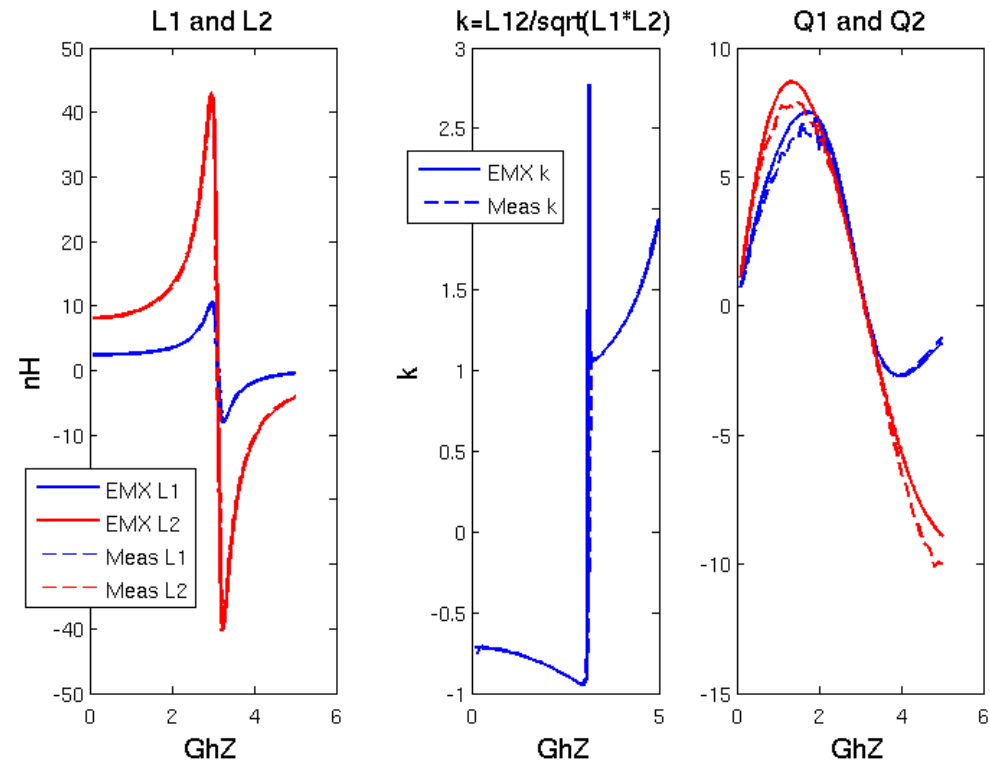
Courtesy: TSMC. 65nm RFCMOS, 9LM thick metal technology. Published at RFIC 2009

"Including Pattern-Dependent Effects in Electromagnetic Simulations of On-Chip Passive Components", Integrand and TSMC

Transformer



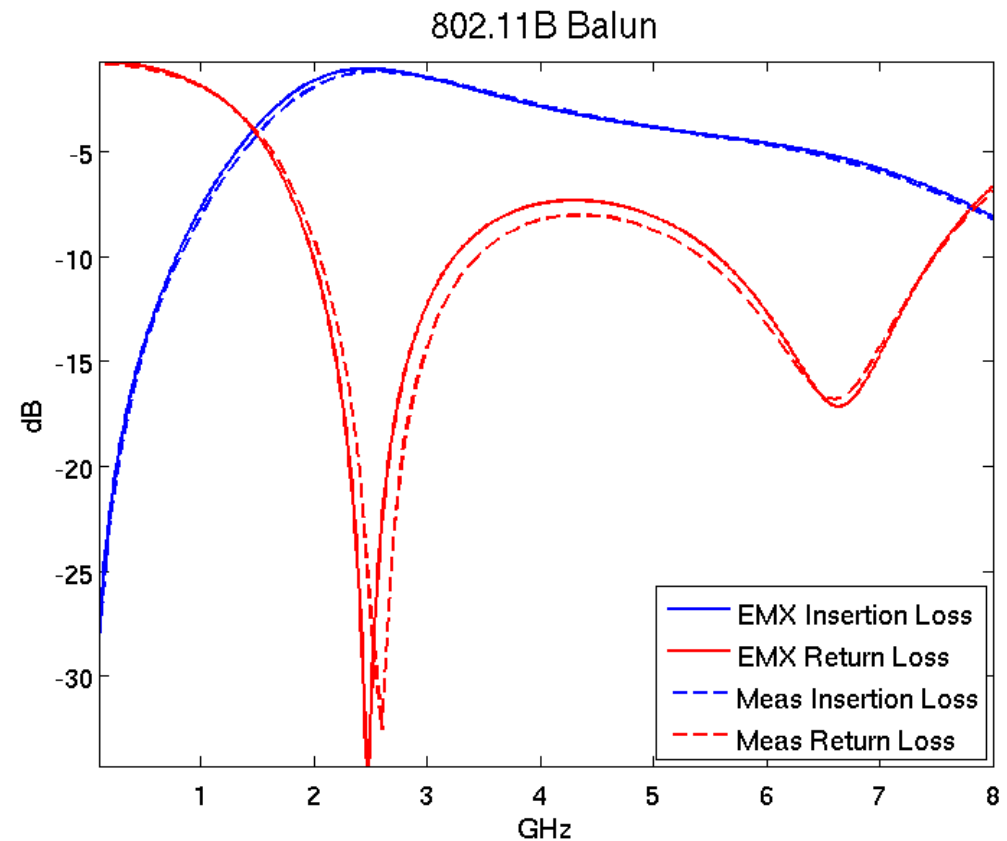
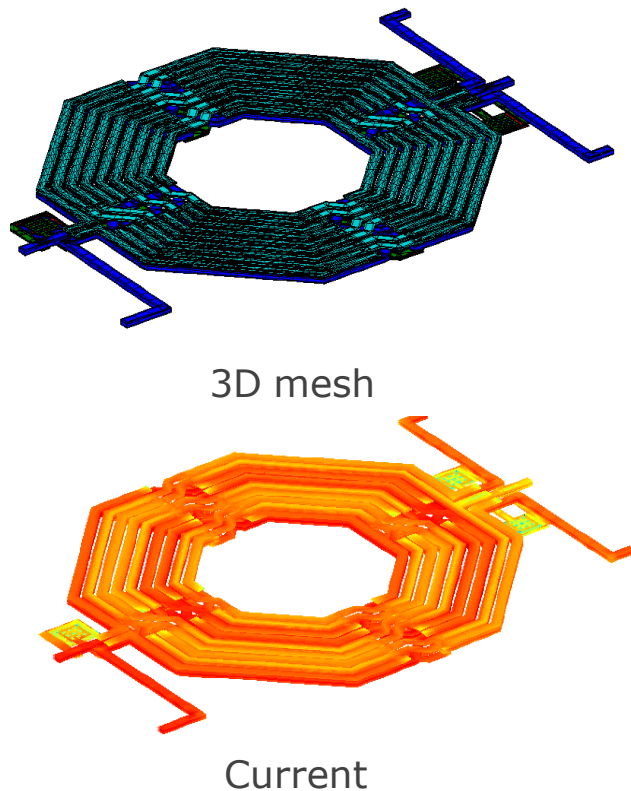
802.11B Transformer



| Example | Ports | Freq Range | Size | 1 CPU | | 8 CPU's | |
|-------------|-------|--------------|--------|--------|--------|---------------|--------------|
| | | | | Mem. | Time | Mem. | Time |
| Transformer | 4 | 0.1GHz-10GHz | 81,405 | 1234MB | 28m48s | 2016MB | 6m01s |

Courtesy: UMC. 90nm RFCMOS, 8LM thick metal technology. Published at CICC 2007
 "Synthesis of Optimal On-Chip Baluns", Integrand and UMC

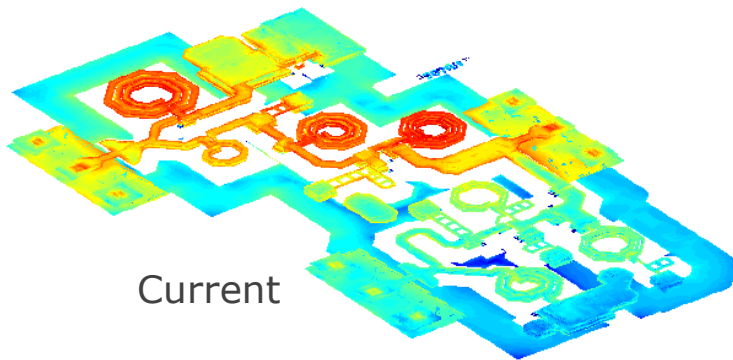
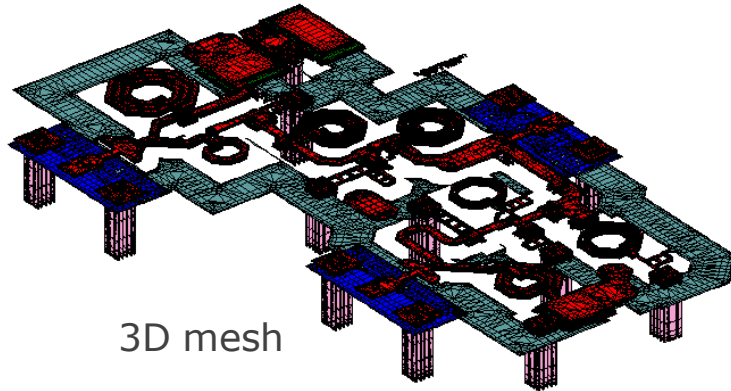
Balun (with MiM caps)



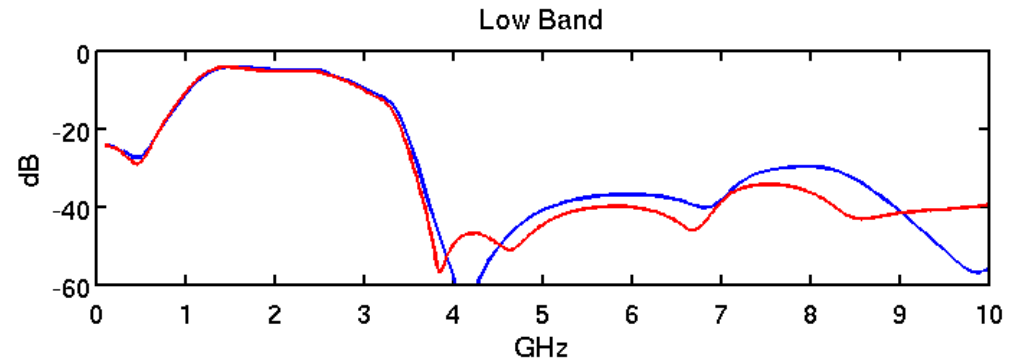
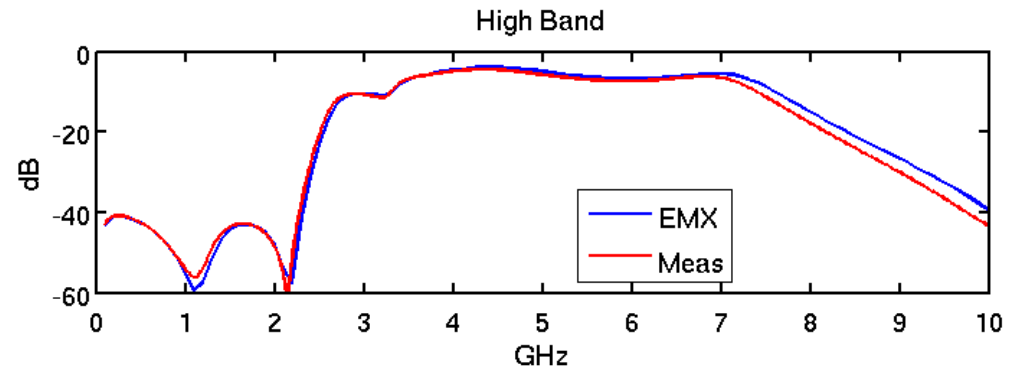
| Example | Ports | Freq Range | Size | 1 CPU | | 8 CPUs | |
|---------|-------|--------------|--------|--------|--------|---------------|--------------|
| | | | | Mem. | Time | Mem. | Time |
| Balun | 5 | 0.1GHz-10GHz | 89,174 | 1449MB | 38m48s | 2584MB | 8m43s |

Courtesy: UMC. 90nm RFCMOS, 8LM thick metal technology. Published at CICC 2007
 "Synthesis of Optimal On-Chip Baluns", Integrand and UMC

BiCMOS Diplexer (with Thru Silicon Vias)

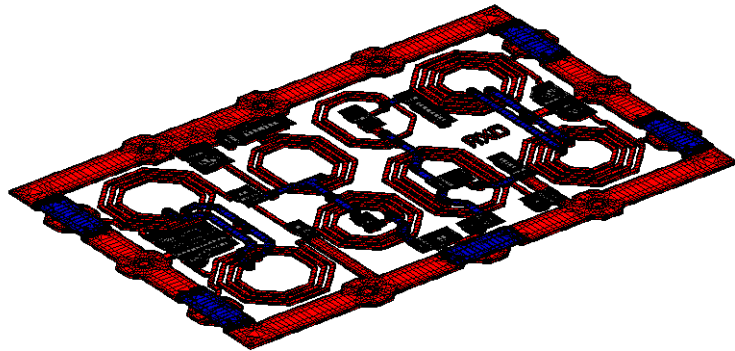


CMOS Diplexer

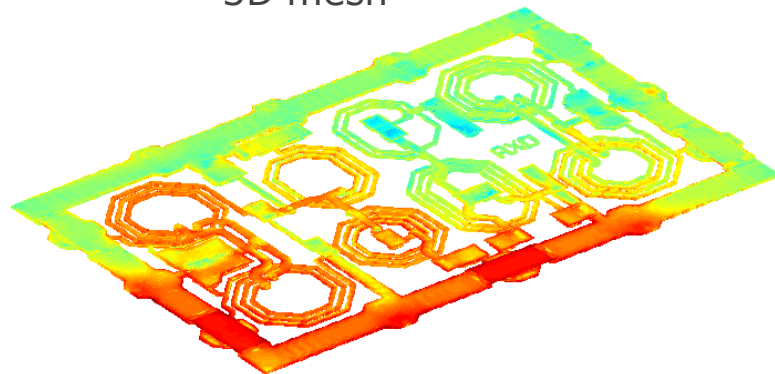


| Example | Ports | Freq Range | Size | 1 CPU | | 8 CPUs | |
|---------------|-------|--------------|---------|--------|---------|---------------|---------------|
| | | | | Mem. | Time | Mem. | Time |
| CMOS Diplexer | 3 | 0.1GHz-10GHz | 195,009 | 4778MB | 374m18s | 8062MB | 65m41s |

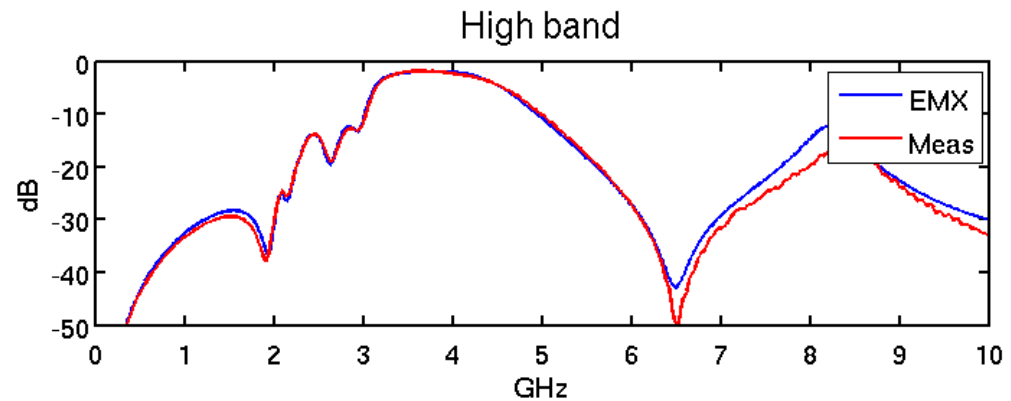
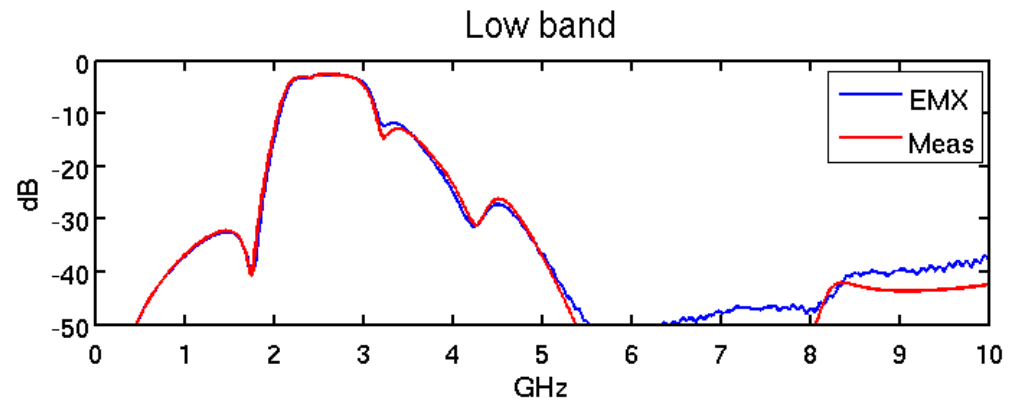
IPD Diplexer



3D mesh



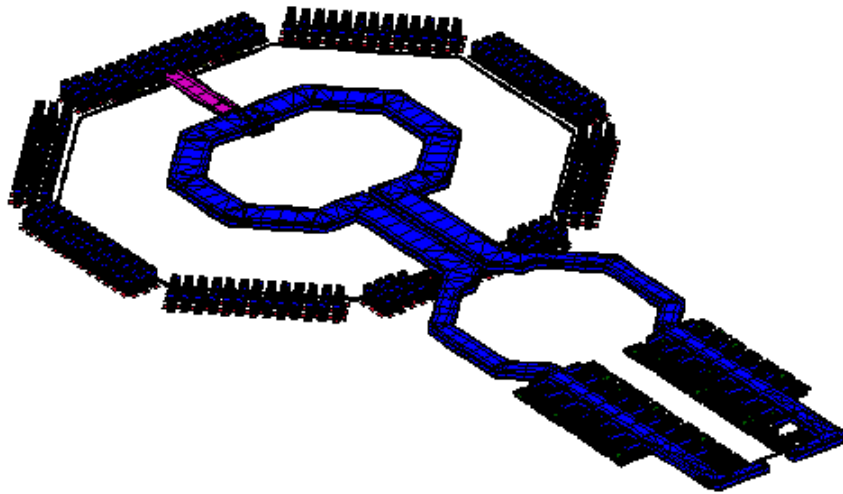
Current



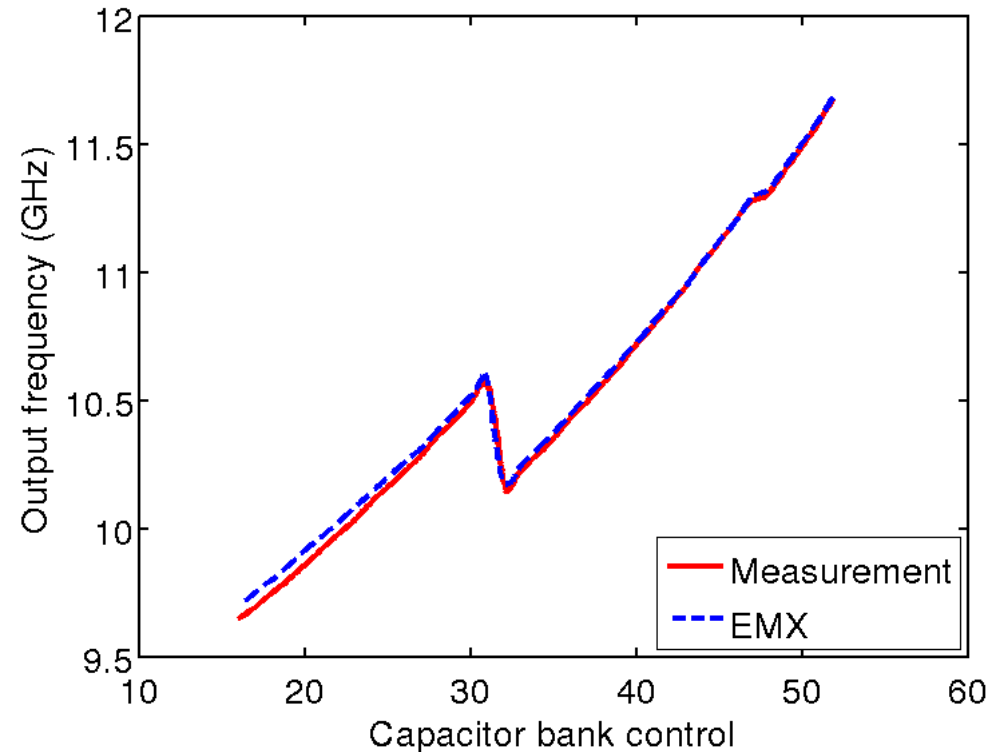
| Example | Ports | Freq Range | Size | 1 CPU | | 8 CPUs | |
|--------------|-------|--------------|---------|--------|---------|---------------|---------------|
| | | | | Mem. | Time | Mem. | Time |
| IPD Diplexer | 12 | 0.1GHz-10GHz | 238,849 | 1932MB | 414m21s | 5449MB | 89m18s |

Courtesy: STATChipPAC, IPD technology (8um Cu on high resistivity Si substrate)

CMOS VCO



3D mesh (inductor+ capacitor bank)



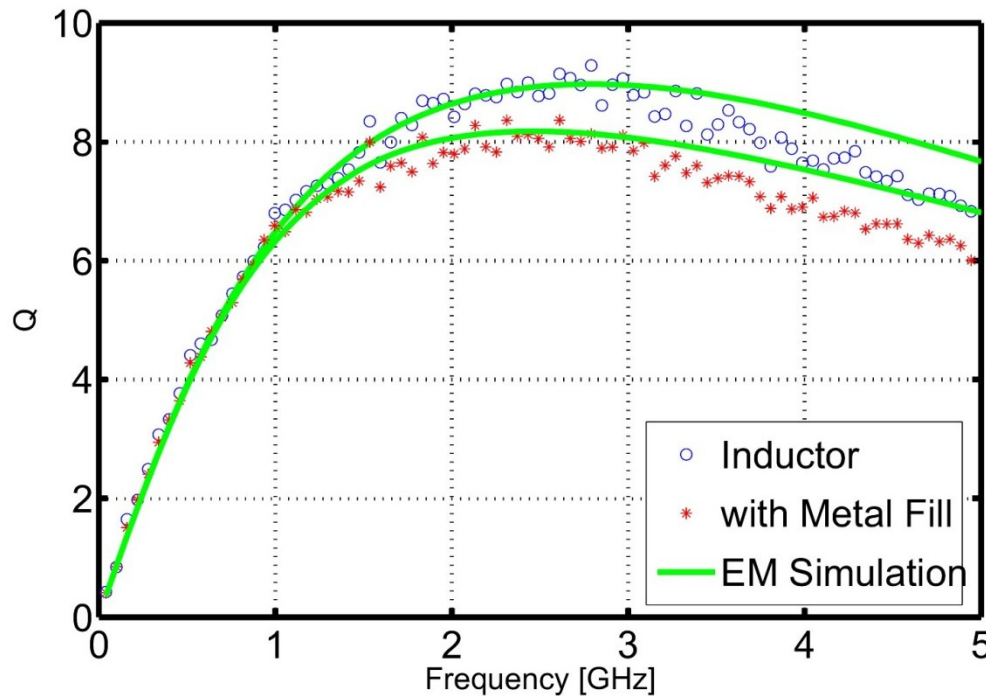
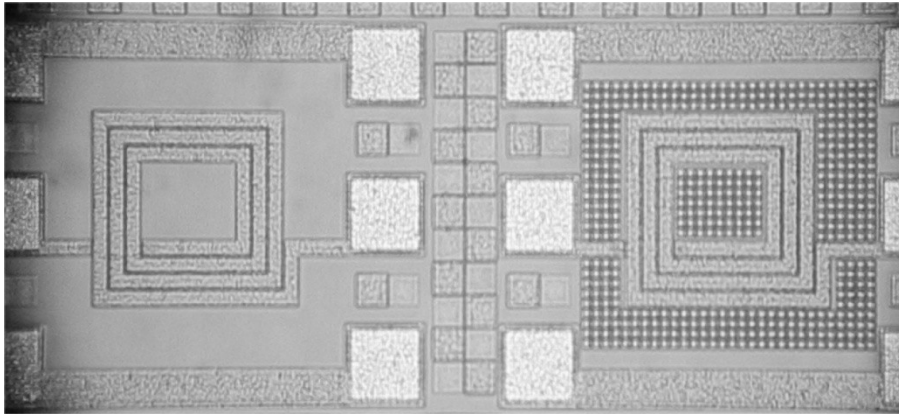
| Example | Ports | Freq Range | Size | 1 CPU | | 8 CPUs | |
|----------|-------|--------------|---------|--------|---------|----------------|---------------|
| | | | | Mem. | Time | Mem. | Time |
| CMOS VCO | 20 | 0.1GHz-20GHz | 137,694 | 5216MB | 399m41s | 18878MB | 98m19s |

Benchmark Summary

| Example | Ports | Freq Range | Size | 1 CPU | | 8 CPUs | |
|------------------|-------|--------------|---------|--------|---------|----------------|---------------|
| | | | | Mem. | Time | Mem. | Time |
| Planar Inductor | 2 | 0.2GHz-30GHz | 13,181 | 193MB | 3m29s | 790MB | 1m48s |
| Stacked Inductor | 2 | 0.2GHz-20GHz | 10,407 | 453MB | 6m58s | 688MB | 4m42s |
| MoM capacitor | 2 | 0.2GHz-20GHz | 48,997 | 1140MB | 19m12s | 2591MB | 5m59s |
| Transformer | 4 | 0.1GHz-10GHz | 81,405 | 1234MB | 28m48s | 2016MB | 6m01s |
| Balun | 5 | 0.1GHz-10GHz | 89,174 | 1449MB | 38m48s | 2584MB | 8m43s |
| CMOS Diplexer | 3 | 0.1GHz-10GHz | 195,009 | 4778MB | 374m18s | 8062MB | 65m41s |
| IPD Diplexer | 12 | 0.1GHz-10GHz | 238,849 | 1932MB | 414m21s | 5449MB | 89m18s |
| CMOS VCO | 20 | 0.1GHz-20GHz | 137,694 | 5216MB | 399m41s | 18878MB | 98m19s |

- The new multi-threaded EMX is 2-3X faster for small examples and 5-6X faster for larger examples on an 8 CPU machine.
- The memory for the multi-threaded version goes up at a slower rate than the speedup.

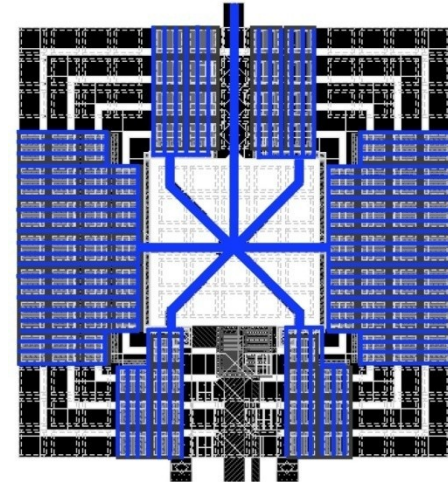
Metal Fill



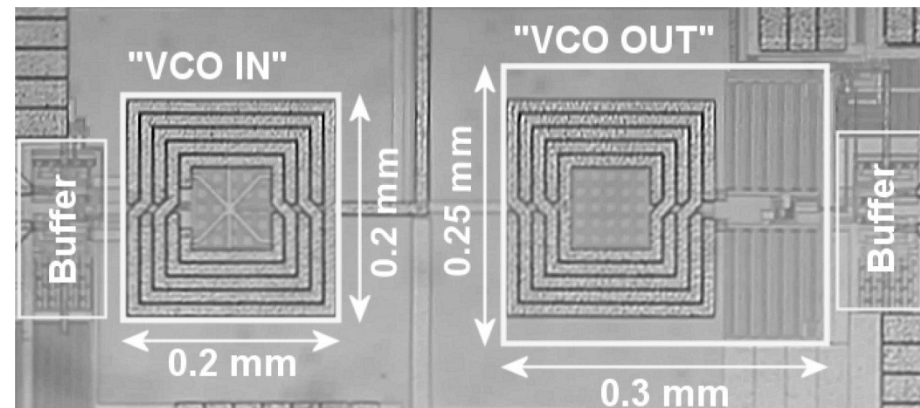
The effect of Metal Fill inside inductor was studied using EMX by Columbia University. (CICC 2005)

VCO in Coil

Inductor with Varactor/MOM
Capacitor acting as a substrate
shield

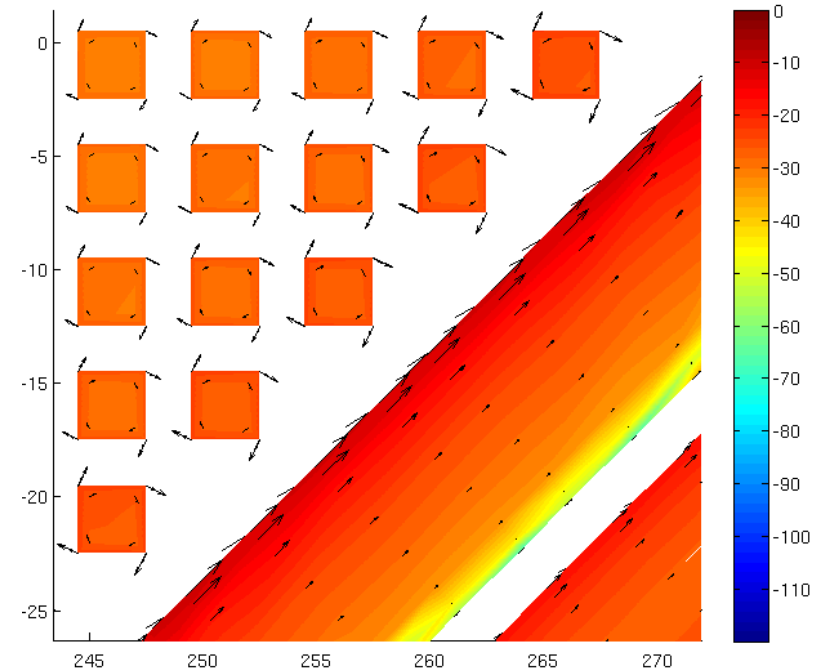
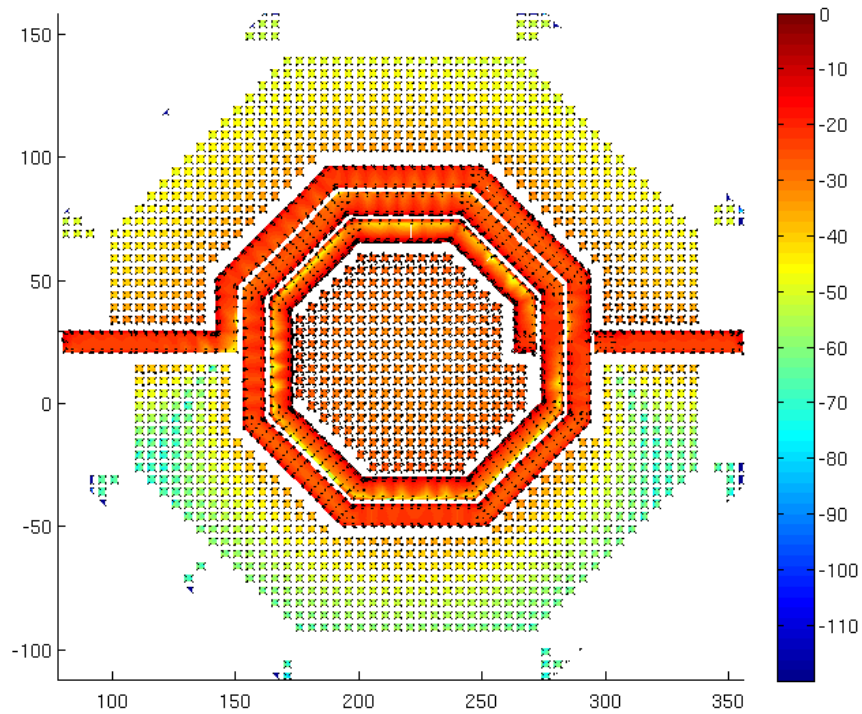


- Equal performance in phase noise and output power as compared to a traditional VCO while **reducing design area by 47%.**



(Columbia University, CICC 2005)

Dummy fill simulation

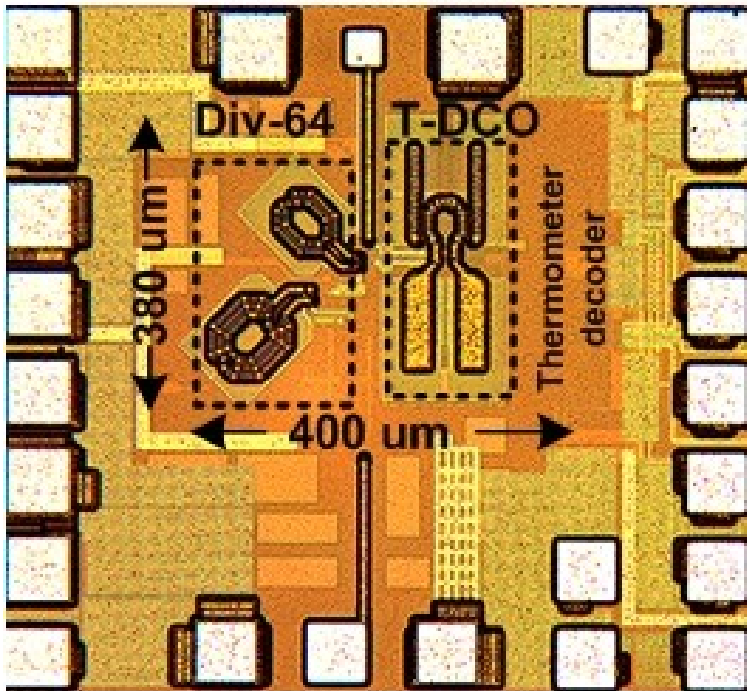


EMX used to model circulating currents in dummy fill

60-GHz DCO Test Chips

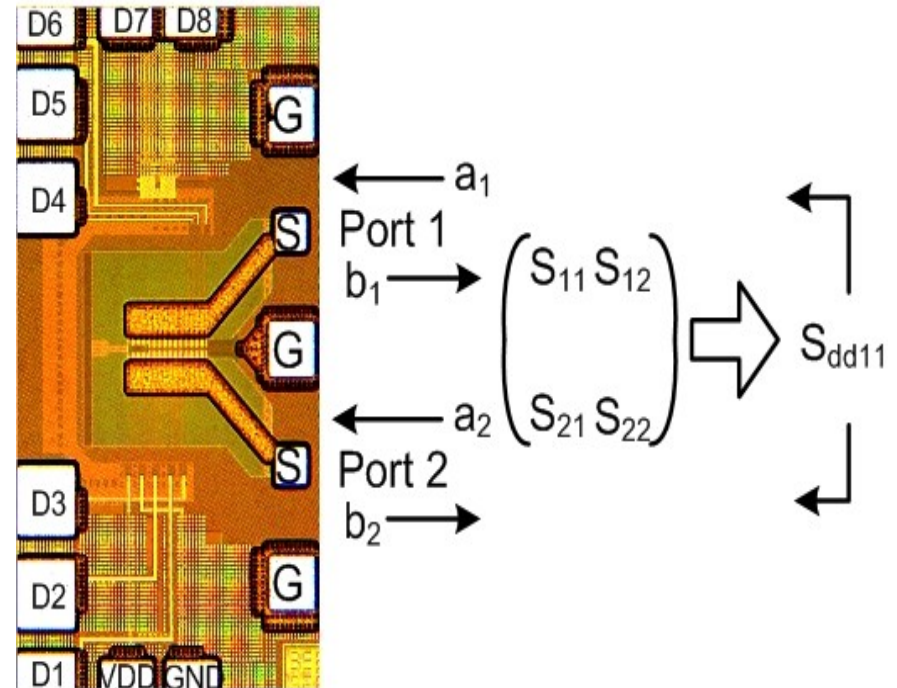
[published at RFIC 2012/ ISSCC 2013]: TU Delft, J.R. Long's group

T-DCO 60 GHz output



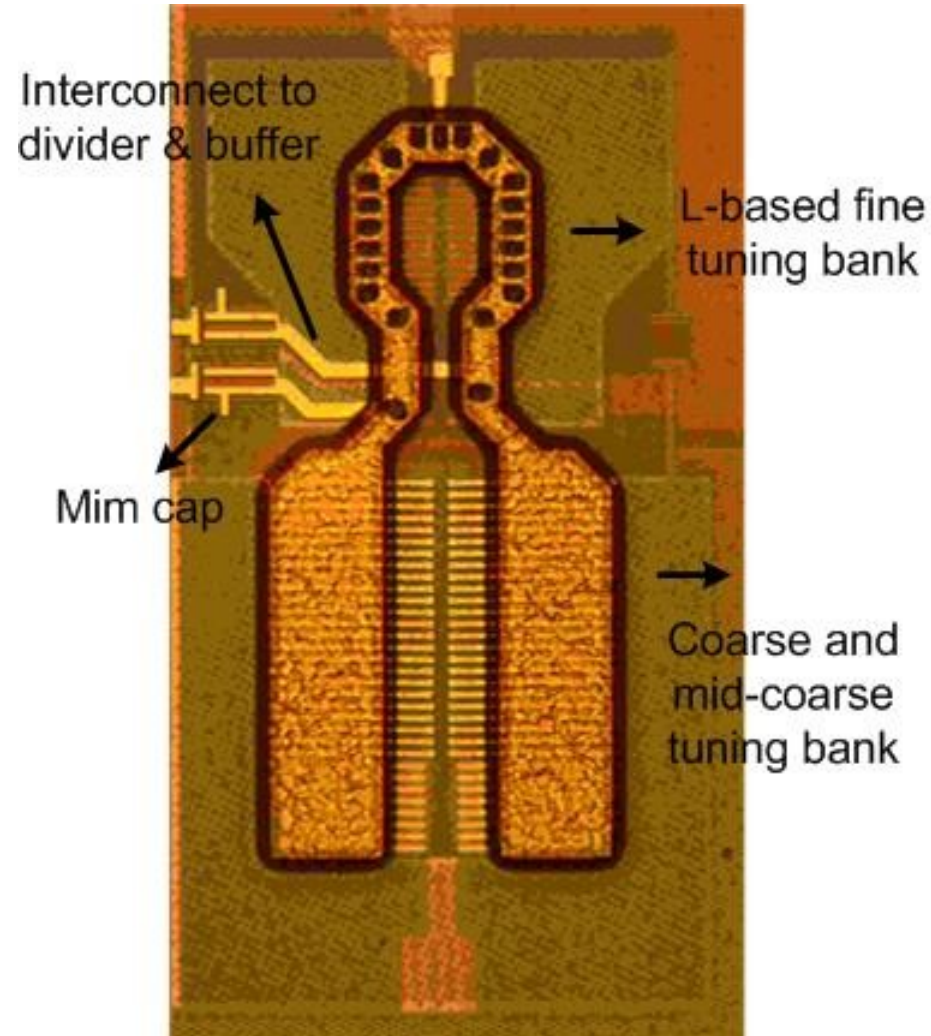
Div. 64 output

Transmission line testchip



Complete L-DCO tank EM simulation

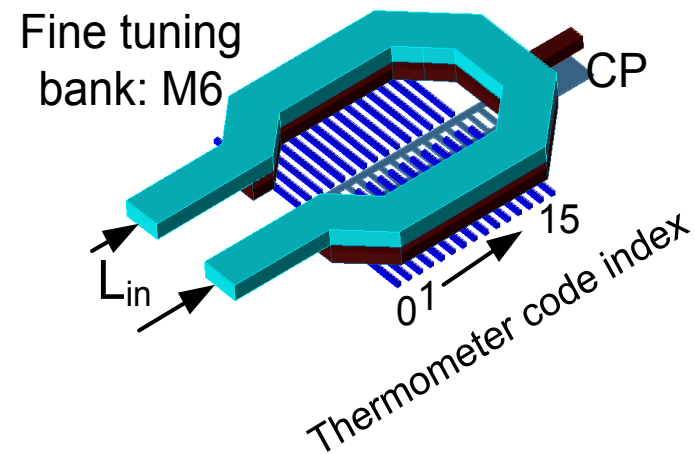
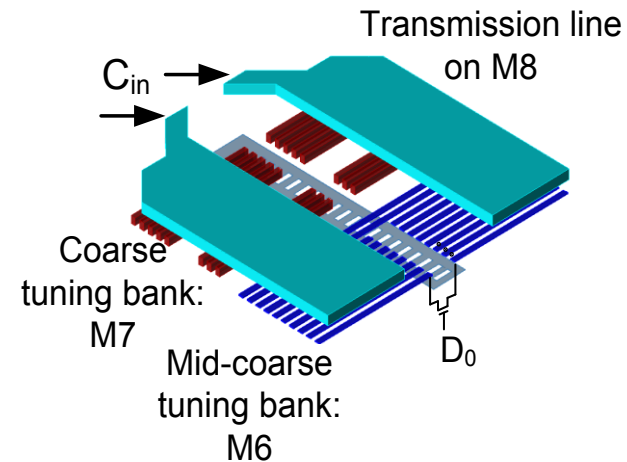
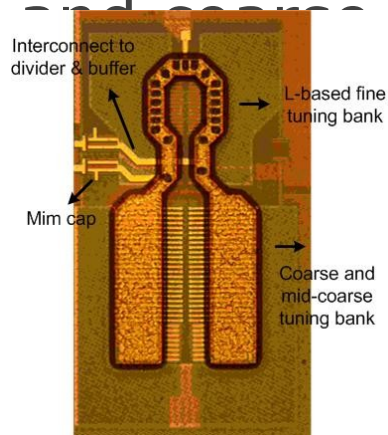
- Including:
 - Coarse, mid-coarse tuning bank
 - Fine tuning bank
 - Interconnection to divider and buffer
 - Mimcap for AC coupling
 - Ground ring
- 100+ port EMX simulation



T-line and inductor tuning

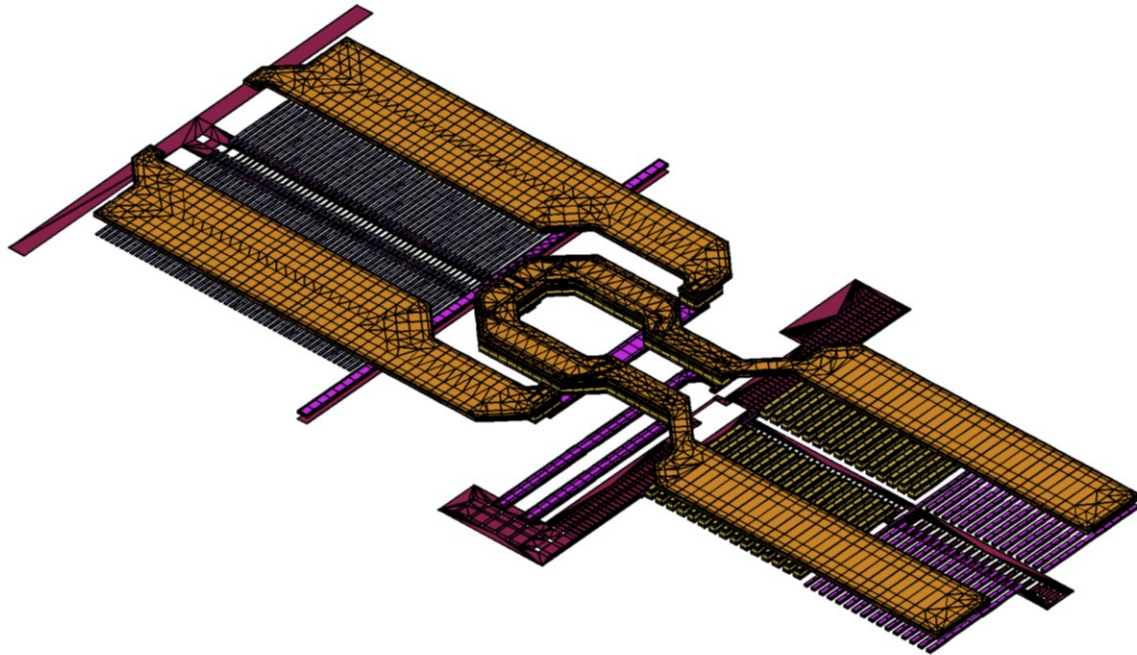
- Passive structures with tuned by capacitive loading

- Transmission line with fine and coarse cap



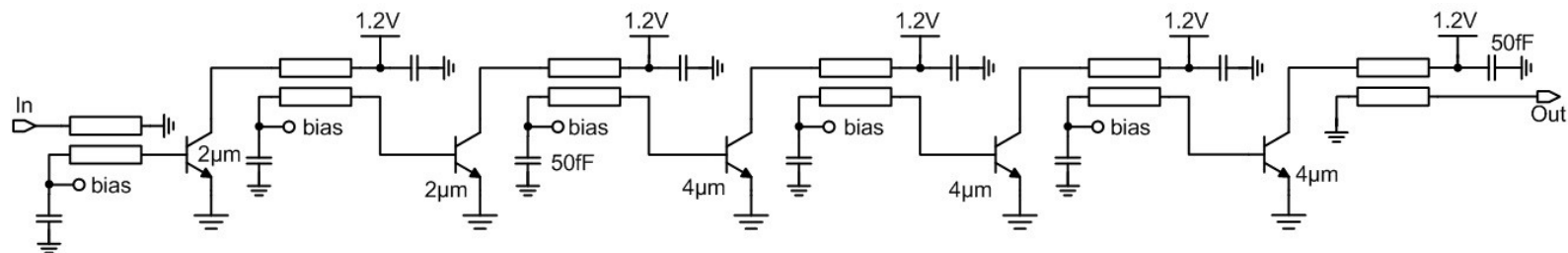
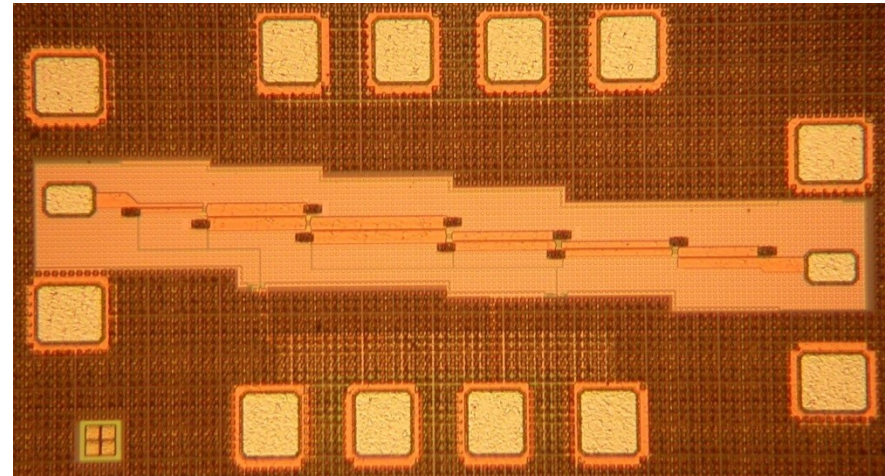
Full DCO tank simulation in EMX

- EMX simulation of 60GHz DCO
 - TL-based coarse and mid-coarse tuning bank, transformer based interconnect, ground plane
 - Ports: 175
 - Layout size 400x200 μm^2
 - Computational resources
 - 3GB memory
 - 8 CPU (2.2GHz)
 - 3 hours of sim time



180GHz Amplifier

- D-band amplifier
- 6dB coupler
- 180GHz H₂O attenuation window
- Atmosphere monitoring

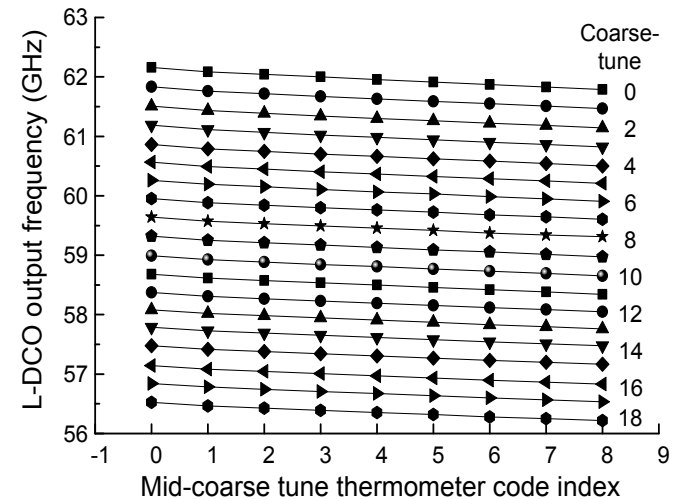
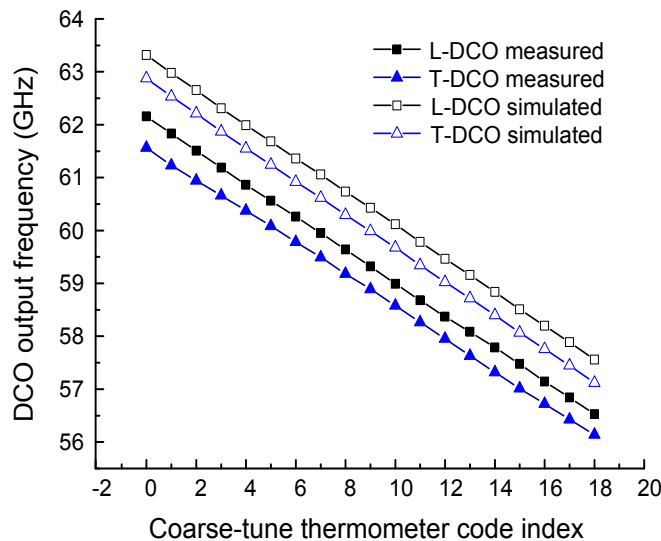
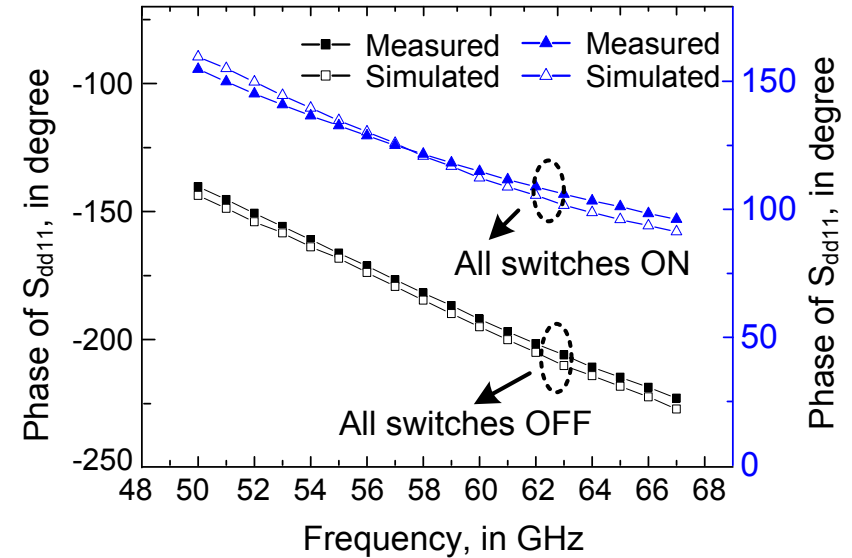
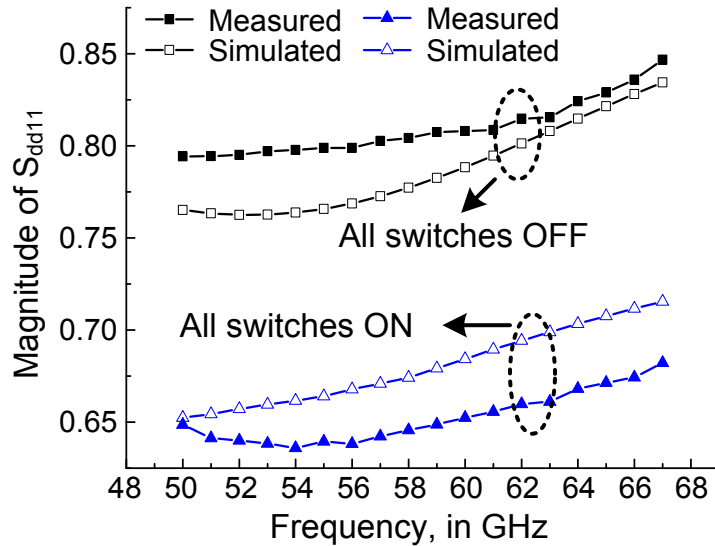


University of Toronto

IMS 2012 (private communication)

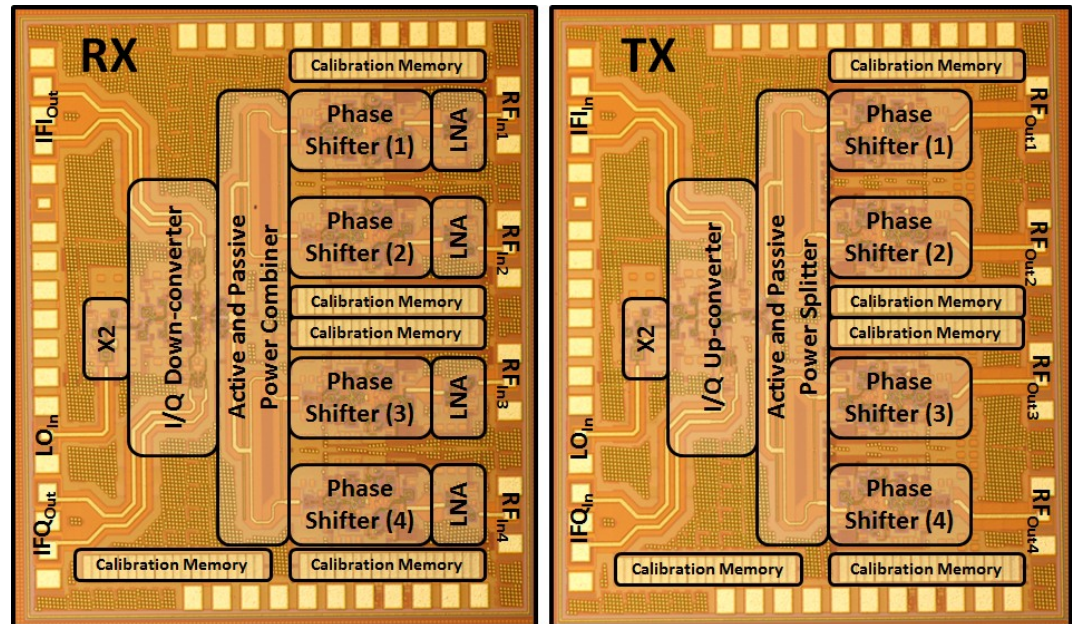
Ionniss Sarkas, Sorin Voinigescu

Measured results

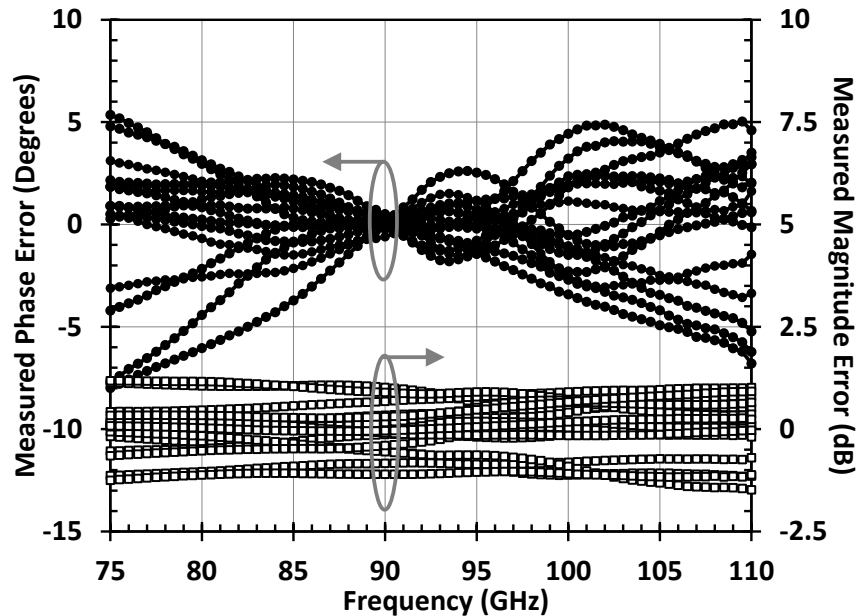


W-band chip

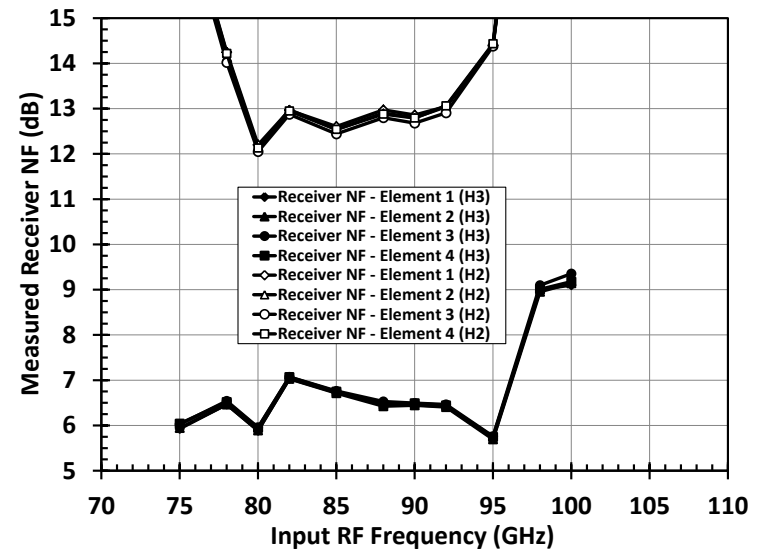
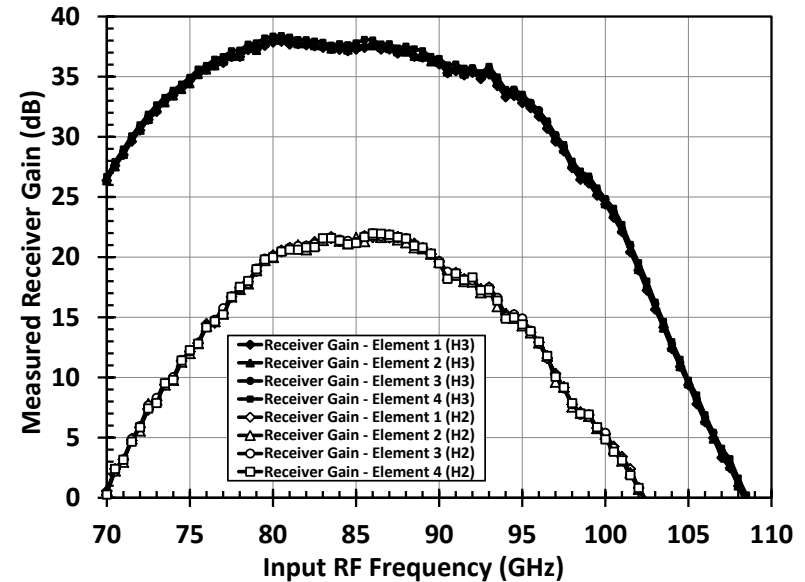
- All passive traces modeled with EMX
- Wilkinson Divider
- Transformer Hybrid architecture
- MM wave passive circuits. Not easy to construct a discrete component equivalent
- Need full S-parameter EM simulation
- All simulations in the 70GHz to 200GHz range



Measured results

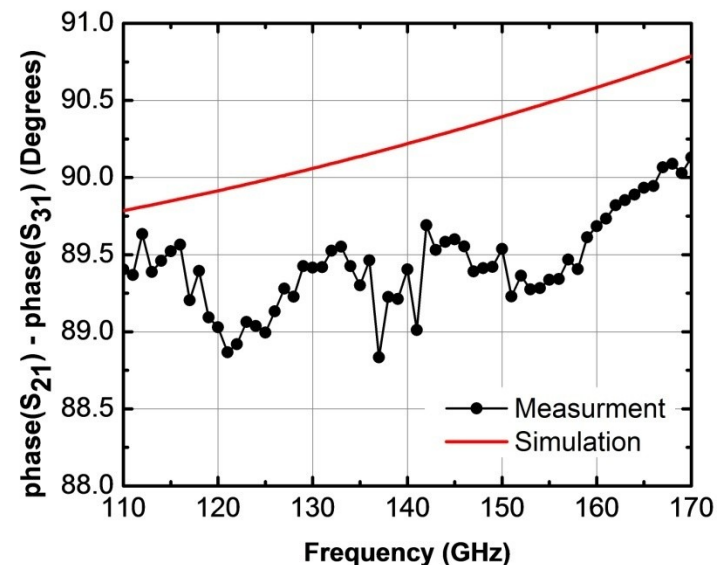
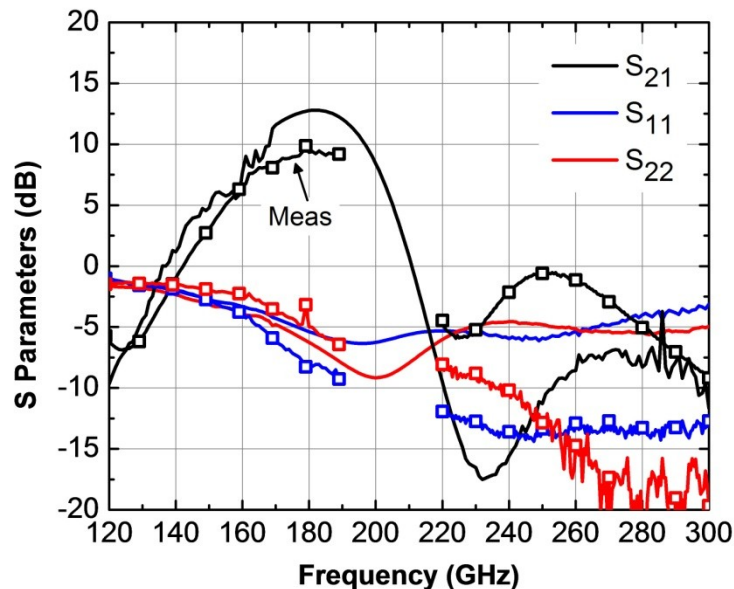
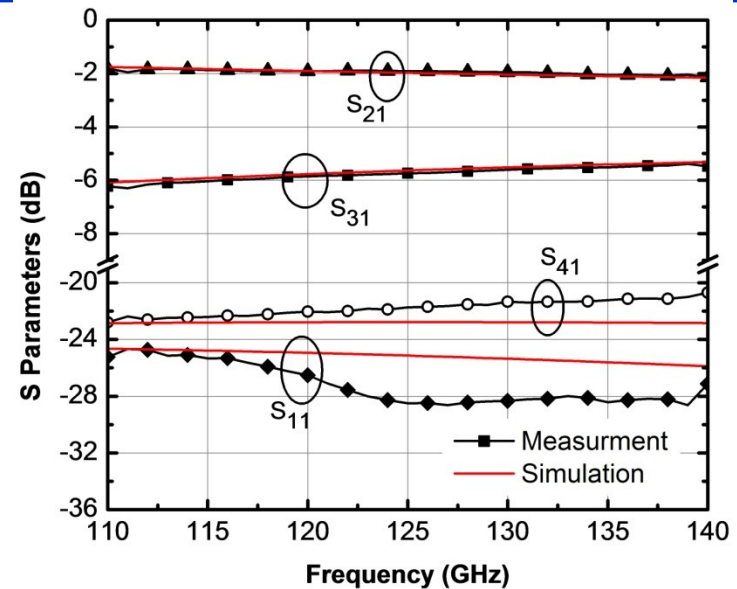
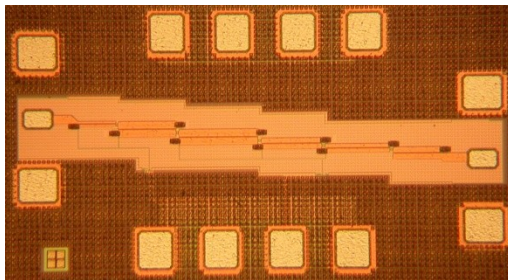


Single Slice Phase/Mag Accuracy

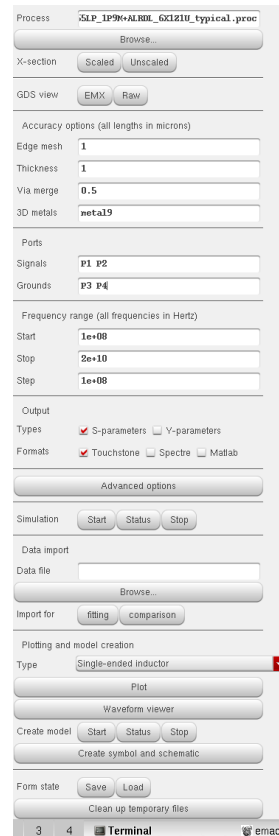
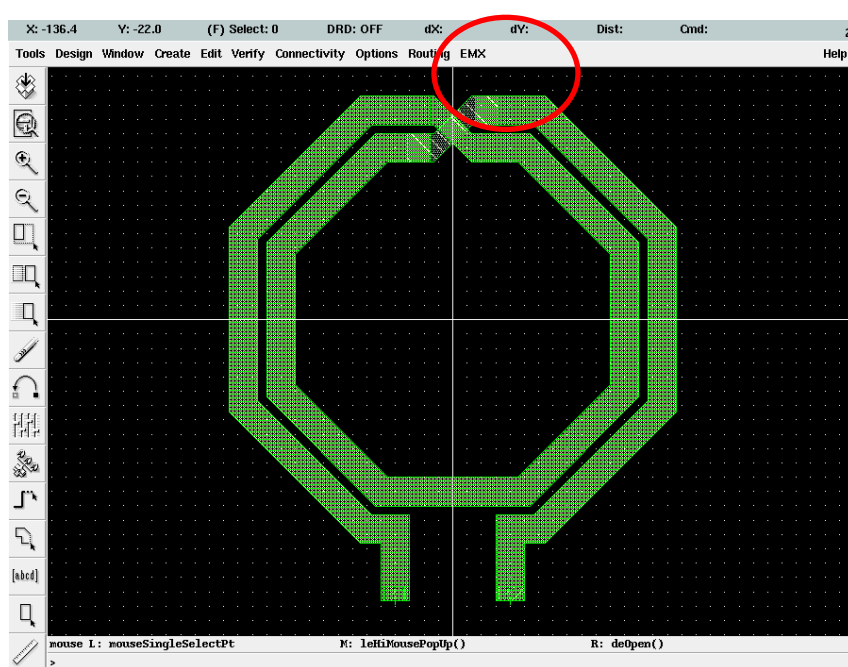


6dB coupler and amplifier

- S-parameter measurements of 6dB coupler up to 180GHz

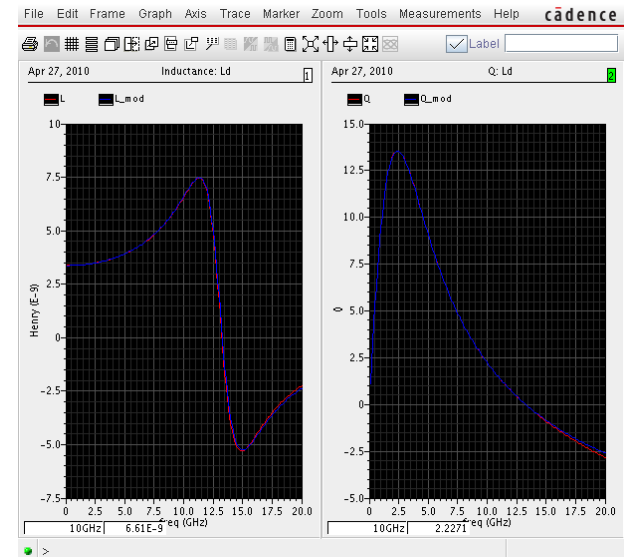


EMX interface to Virtuoso



| | | |
|---------|--------|-------------------|
| 704.220 | metal5 | h=0.775 µm, c=4.2 |
| 704.420 | metal5 | h=0.775 µm, c=4.2 |
| 704.585 | metal5 | h=0.775 µm, c=4.2 |
| 704.875 | metal5 | h=0.775 µm, c=4.2 |
| 704.705 | metal5 | h=0.775 µm, c=4.2 |
| 704.565 | metal5 | h=0.775 µm, c=4.2 |
| 704.245 | metal5 | h=0.775 µm, c=4.2 |
| 704.165 | metal5 | h=0.775 µm, c=4.2 |
| 704.855 | metal5 | h=0.775 µm, c=4.2 |
| 704.775 | metal5 | h=0.775 µm, c=4.2 |
| 704.615 | metal5 | h=0.775 µm, c=4.2 |
| 704.365 | metal5 | h=0.775 µm, c=4.2 |
| 704.000 | metal5 | h=0.775 µm, c=4.2 |

process file



From layout to Spice
model in seconds

Simulation, modeling and plotting

Close

Help

Process

cinterface/processes/generic65.prod

Browse...

X-section

Scaled

Unscaled

GDS view

EMX

Raw

Accuracy options (all lengths in microns)

Edge mesh

1

Thickness

1

Via merge

0.5

3D metals

1

Ports

Signals

P1 P2

Grounds

Frequency range (all frequencies in Hertz)

Start

1e+08

Stop

2e+10

Step

1e+08

Output

Types

☒ S-parameters

☐ Y-parameters

Formats

☒ Touchstone

☐ Spectre

☐ Matlab

Advanced options

Simulation

Start

Status

Stop

Data import

Data file

Browse...

Import for

fitting

comparison

Plotting and model creation

Type

Single-ended inductor

Plot

Waveform viewer

Create model

Start

Status

Stop

Create symbol and schematic

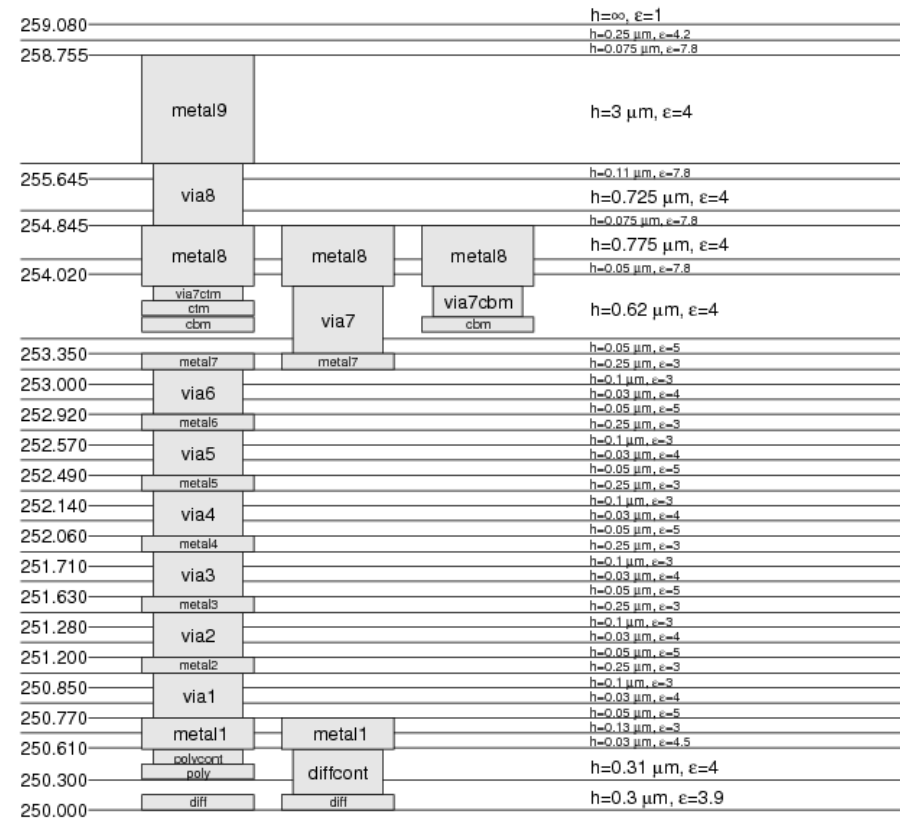
Form state

Save

Load

Close up temporary files

View the
process
file



h=250 μm, ε=11.9, 12.5 Ω-cm, 8 S/m

0.000

metal9: h=3 μm, 6 mΩ/sq
 metal8: h=1 μm, 20 mΩ/sq
 ctm: h=0.1 μm, 20 Ω/sq
 cbm: h=0.2 μm, 0.5 Ω/sq
 metal7: h=0.25 μm, 0.18 Ω/sq, bias 10 nm
 metal6: h=0.25 μm, 0.18 Ω/sq, bias 10 nm
 metal5: h=0.25 μm, 0.18 Ω/sq, bias 10 nm
 metal4: h=0.25 μm, 0.18 Ω/sq, bias 10 nm
 metal3: h=0.25 μm, 0.18 Ω/sq, bias 10 nm
 metal2: h=0.25 μm, 0.18 Ω/sq, bias 10 nm
 metal1: h=0.18 μm, 0.2 Ω/sq, bias 5 nm
 poly: h=0.1 μm, 14.9 Ω/sq, bias -0.5 nm
 diff: h=0.086 μm, 16.9 Ω/sq

via7ctm: h=0.0273 μm, 0.5 Ω/via
 via7cbm: h=0.145 μm, 0.5 Ω/via
 via8: h=0.91 μm, 0.4 Ω/via
 via7: h=0.495 μm, 0.2 Ω/via
 via6: h=0.18 μm, 2 Ω/via
 via5: h=0.18 μm, 2 Ω/via
 via4: h=0.18 μm, 2 Ω/via
 via3: h=0.18 μm, 2 Ω/via
 via2: h=0.18 μm, 2 Ω/via
 via1: h=0.18 μm, 2 Ω/via
 polycont: h=0.17 μm, 20 Ω/via
 diffcont: h=0.504 μm, 26 Ω/via

Close Help

Process

Browse...

X-section

GDS view

Accuracy options (all lengths in microns)

Edge mesh

Thickness

Via merge

3D metals

Ports

Signals

Grounds

Frequency range (all frequencies in Hertz)

Start

Stop

Step

Output

Types ☒ S-parameters ☐ Y-parameters

Formats ☒ Touchstone ☐ Spectre ☐ Matlab

Advanced options

Simulation

Data import

Data file

Browse...

Import for

Plotting and model creation

Type

Plot

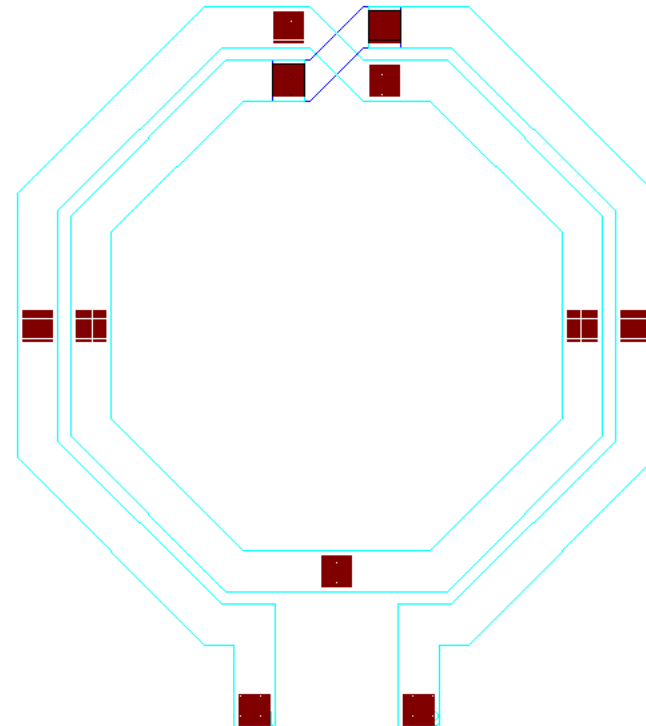
Waveform viewer

Create model

Create symbol and schematic

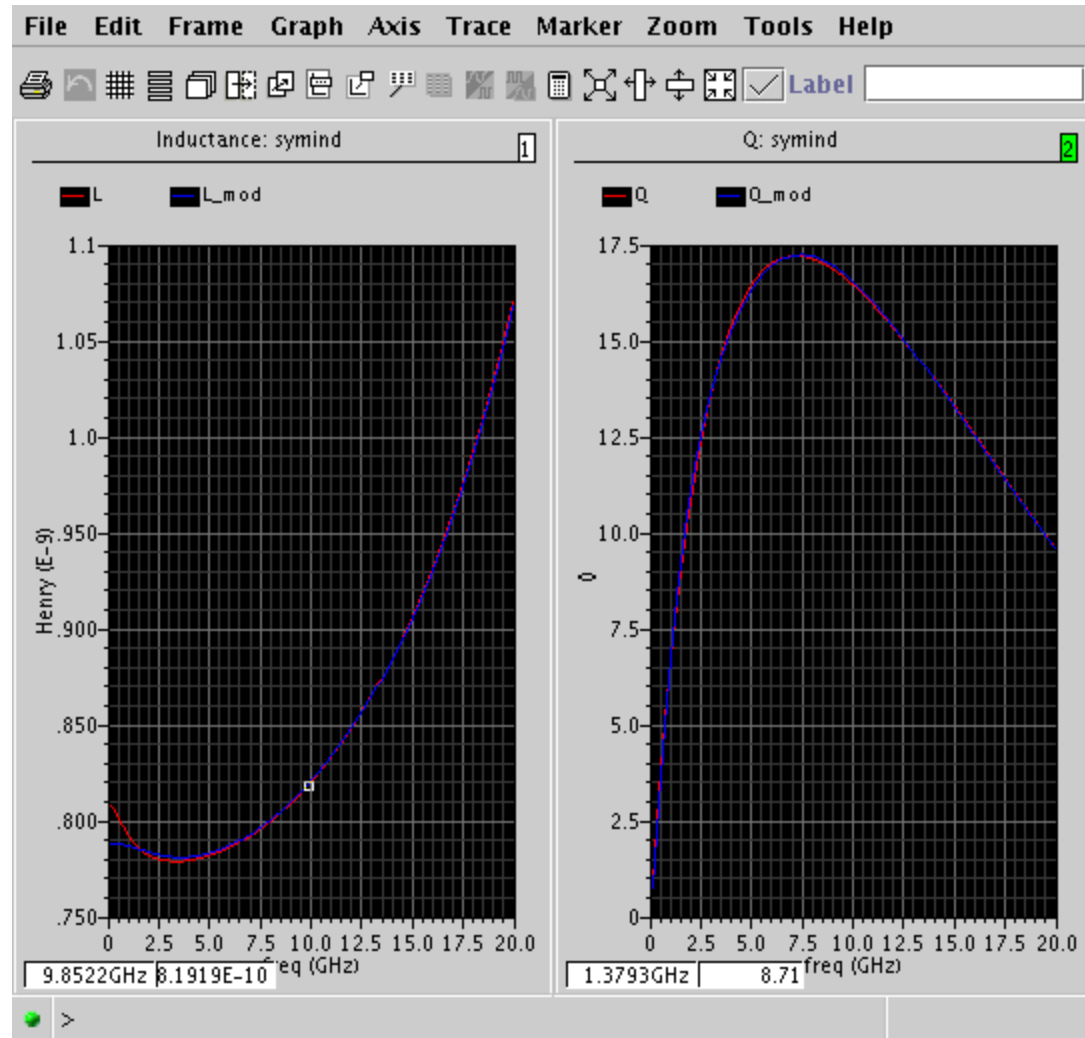
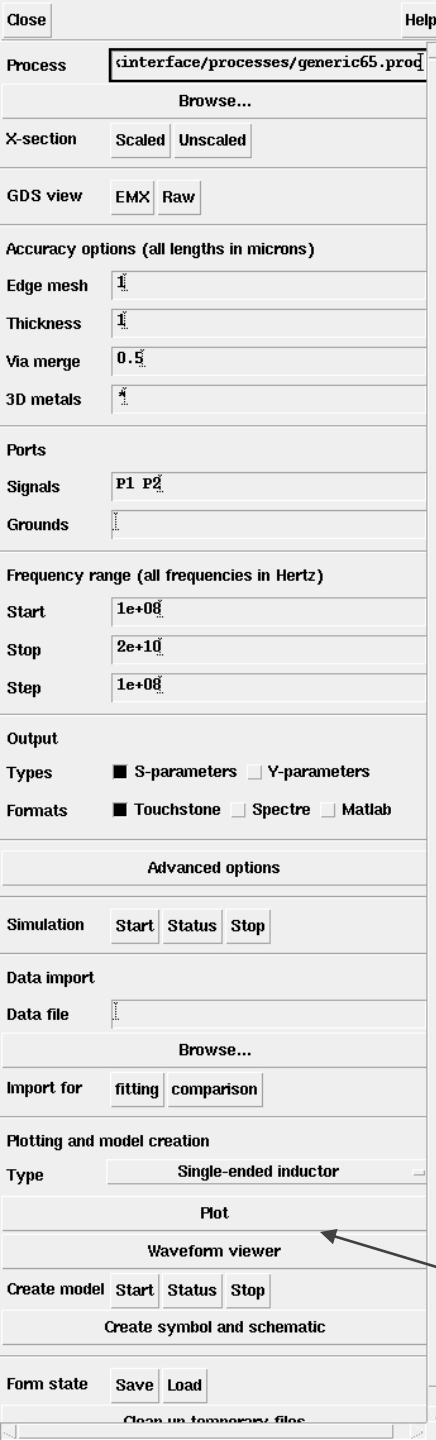
Form state

Close up temporary files



(-127.227, 25.884)

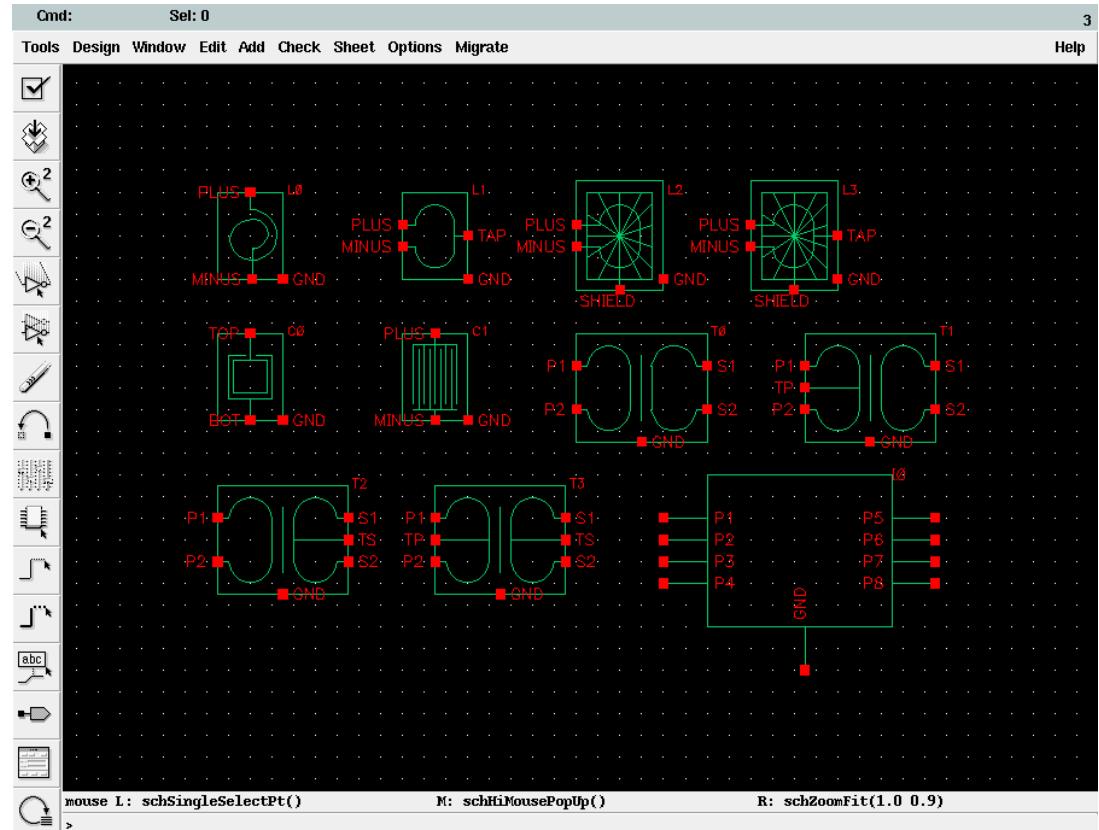
View the raw .gds



Generate/compare model vs EMX simulation

The devices

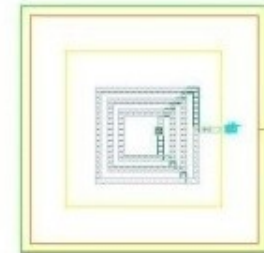
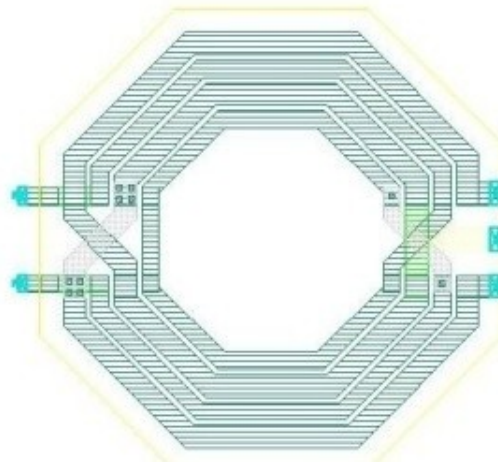
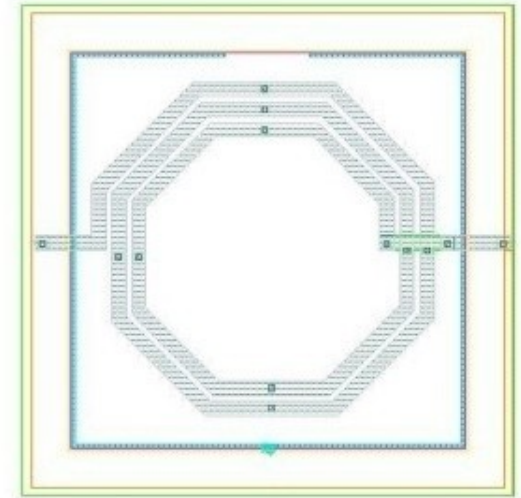
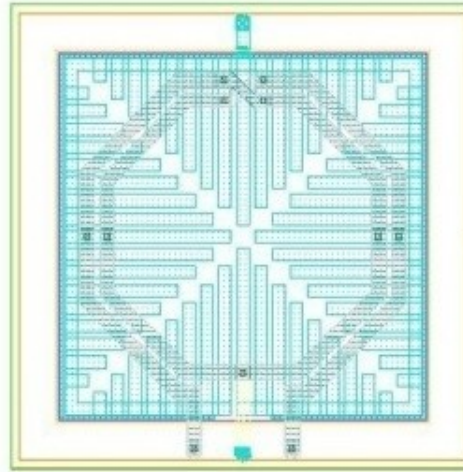
Single-ended inductor
 Differential inductor
 Single-ended shield inductor
 Differential shield inductor
 Center-tapped inductor
 Center-tapped inductor (common mode)
 Center-tapped shield inductor
 Single-ended finger capacitor
 Differential finger capacitor
 MiM capacitor
 Transformer, no taps
 Transformer, tapped primary
 Transformer, tapped secondary
 Transformer, both tapped
 Tcoil
 N-port



This is the list of currently supported models that can be generated by EMX and Modelgen.

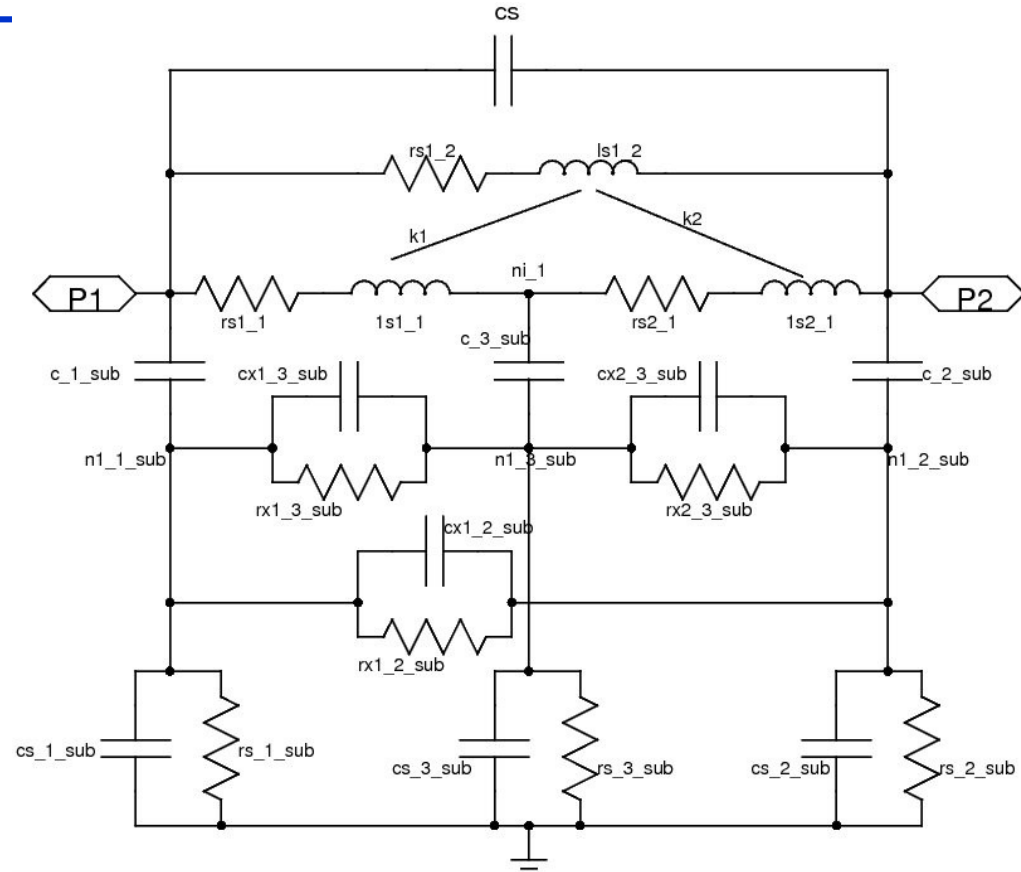
PCELLS

- PCELLS for various components
- Inductors
 - Spiral, Stacked, Symmetric, Peaked
- Transformers
 - 4,5,6 port
- MOM capacitors
- Shields
- DRC clean



Scalable models

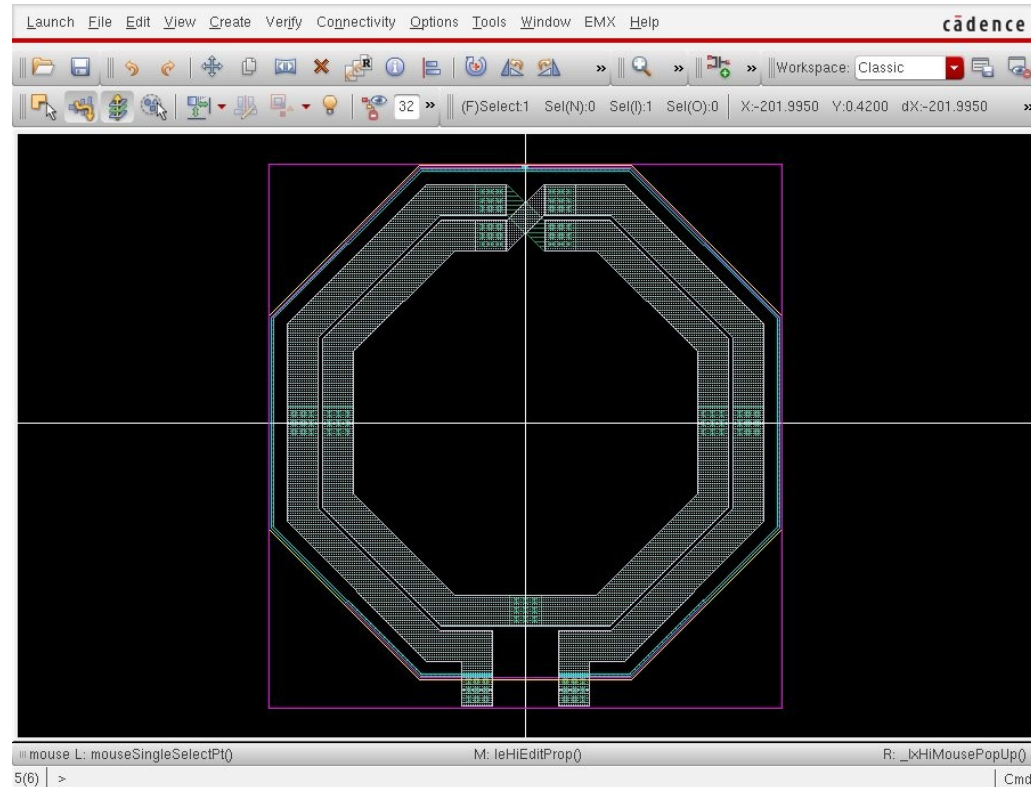
- EMX-Continuum used to generate scalable component models
- 100s of EMX simulations
- Single scalable model is constructed
- Model topology is physics based
- Within a few percent of the EMX simulation
- Models used by TSMC, UMC, GF and IBM



Scalable Model

Optimum component synthesis

- With scalable models it is possible to do a gradient based optimization
- Exploration of design space
 - Maximize Q of inductors
 - Minimize insertion loss of Baluns
- Optimum component in seconds



Optimum inductor

OK

Cancel

Apply

Next

Previous

Help

Attribute

Connectivity

Parameter

Property

ROD

DFM

Condition

Model Name

sym_ind_scalable

Mode

Single Ended

Turns

3

Inner radius

73.57u

Metal width

9.9u

Protection Ring

Freq

2.5G

Inductance

1.99497n

Q

12.34623

Area (um^2)

51480.43

SRF

12.91871G

Parameters

valid

Plot

Plot action

append

Desired inductance

2n

Minimum Q

none

Max area (um^2)

infinite

Delta L (percent)

1

Bandwidth

0

Minimum SRF

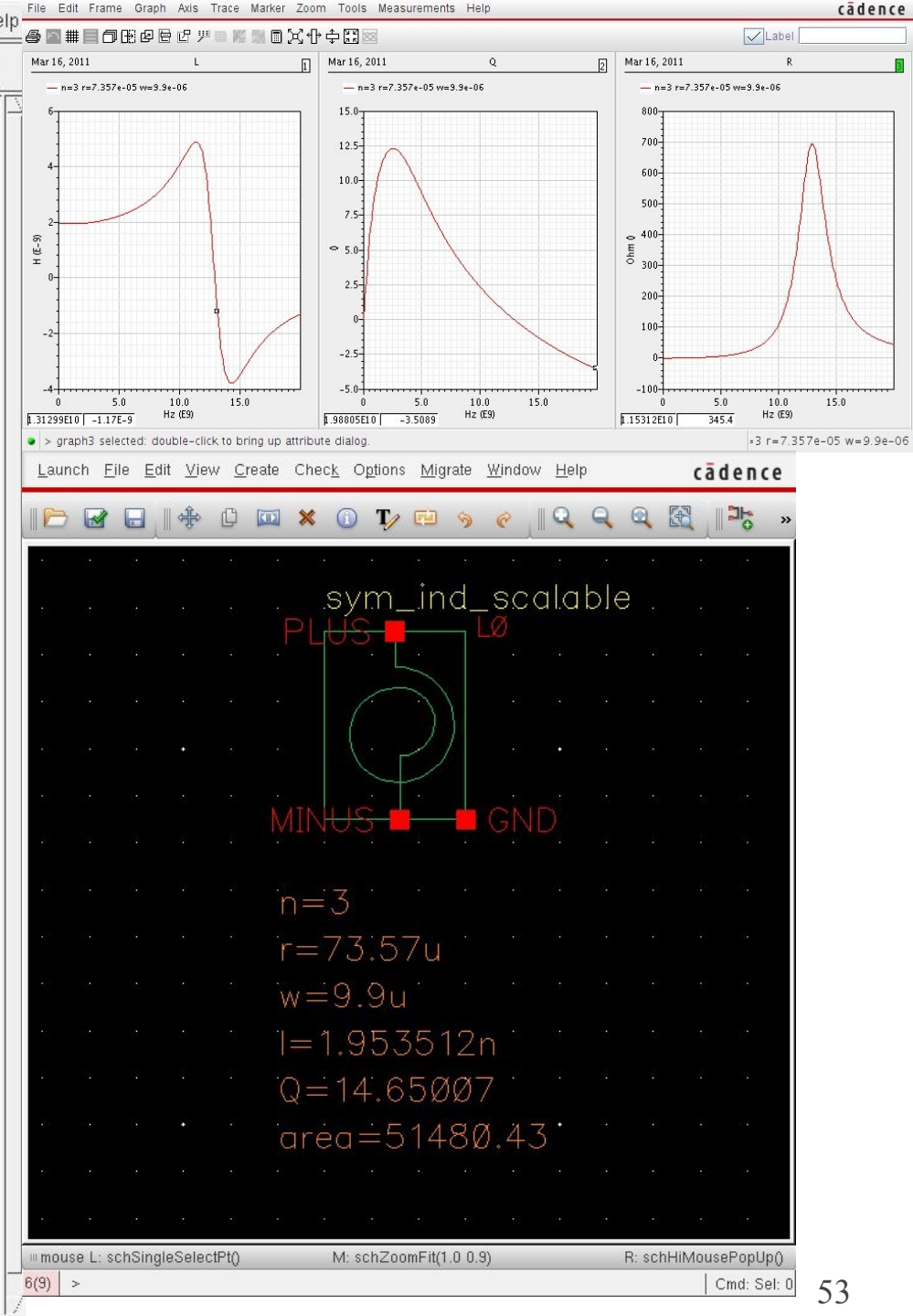
0

Objective

Maximize Q

Find optimal inductor

About optimal inductor finder



Mar 16, 2011

L

n=3 r=7.357e-05 w=9.9e-06

31299E10 -1.17E-9 Hz (E9)

Mar 16, 2011

Q

n=3 r=7.357e-05 w=9.9e-06

98805E10 -3.5089 Hz (E9)

Mar 16, 2011

R

n=3 r=7.357e-05 w=9.9e-06

15312E10 345.4 Hz (E9)

> graph3 selected: double-click to bring up attribute dialog.

Launch

File

Edit

View

Create

Check

Options

Migrate

Window

Help

cadence

File

Edit

View

Create

Check

Options

Migrate

Window

Help

sym_ind_scalable

PLUS

MINUS

GND

L0

n=3

r=73.57u

w=9.9u

l=1.953512n

Q=14.65007

area=51480.43

mouse L: schSingleSelectPt()

M: schZoomFit(1.0 0.9)

R: schHiMousePopUp()

6(9)

>

Cmd: Sel: 0

Using EMX

- Operating Systems
 - 64-bit or 32-bit Linux OS
- Memory
 - 2GB RAM for 32-bit machines
 - As much as you can have for 64-bit machines
 - 8G, 16G, 32G are commonly used by our customers
- Multi-threading feature available
 - 2X-6X faster on an 8CPU machine
- Platform LSF support
 - Bsub for cloud based compute farms
- Auxillary programs in Matlab
 - Plotting and circuit extraction toolkit, EMX meshes, Current Plots, Charge Plots

Conclusions

- EMX
 - Full Wave, 3D simulation, accurate and very fast
 - What goes to mask goes to simulator (vias, slotting, fill)
 - Very easy to learn and use
 - Used for component-level to circuit level simulations
 - Can be used from command line or within Cadence Virtuoso
 - Dramatically reduces design cycle time and enhances productivity
 - Has been adopted by the world's major foundries for all scalable model generation and modeling